

Diagnostics of Reactive Oxygen and Nitrogen Species Generated by Plasma Sources

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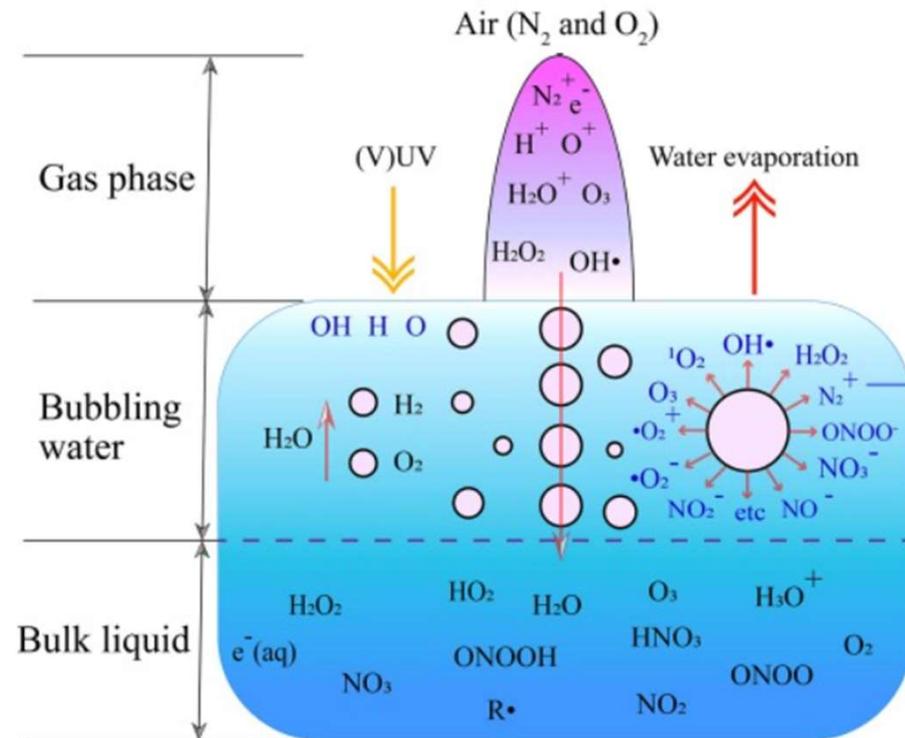
Composition of the plasma

Parameters affecting composition of produced plasma

- The mode of plasma generation,
- Configuration of the plasma equipment,
- Working gas type,
- Gas flow rate,
- Dose of energy input (power, frequency),
- Place of measurement in plasma.

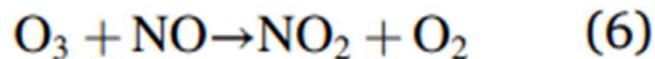
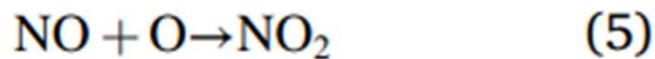
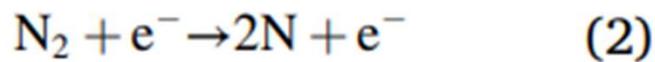
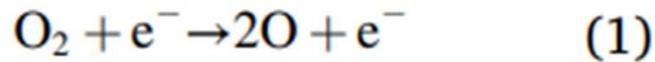
Gases used for the creation of plasma

- Air
- Oxygen
- Nitrogen
- Air-nitrogen
- Air-argon
- Oxygen-nitrogen
- Argon
- Air-oxygen

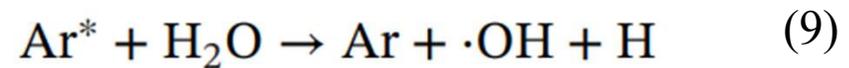
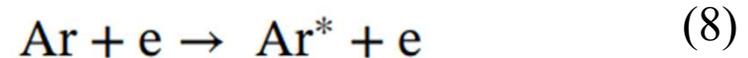
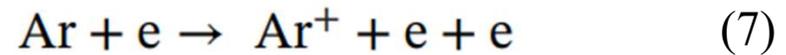


Processes in the plasma

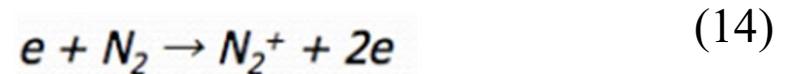
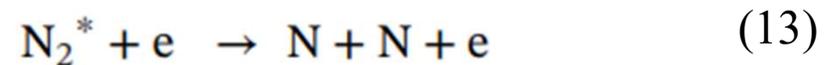
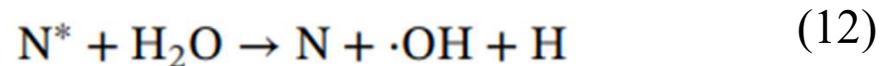
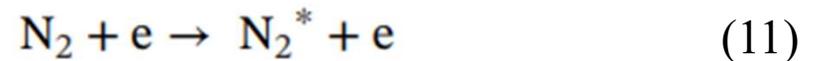
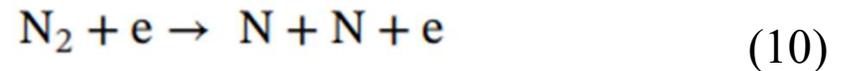
Common pathways for the generation of reactive species in air plasma

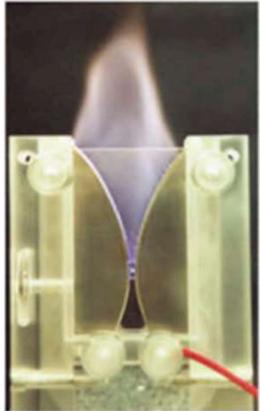


Common pathways for argon plasma



Common pathways for nitrogen plasma



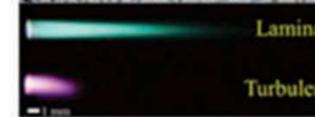
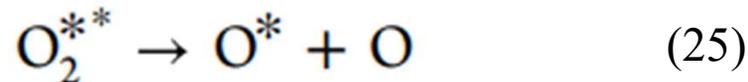
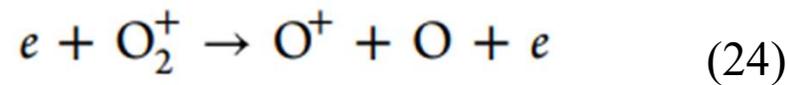
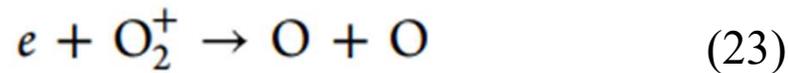
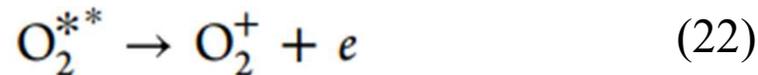
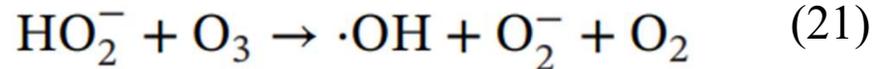
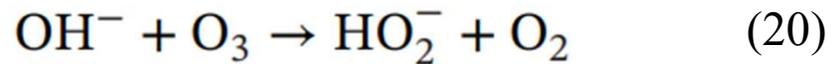
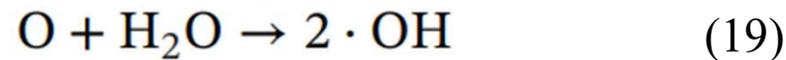
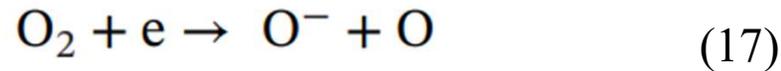
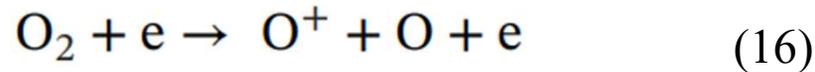


Gliding arc

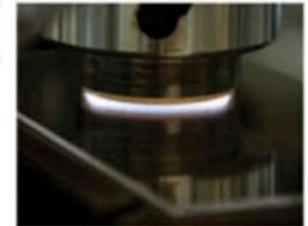


DBD

Common pathways for oxygen plasma



Cold plasma jet

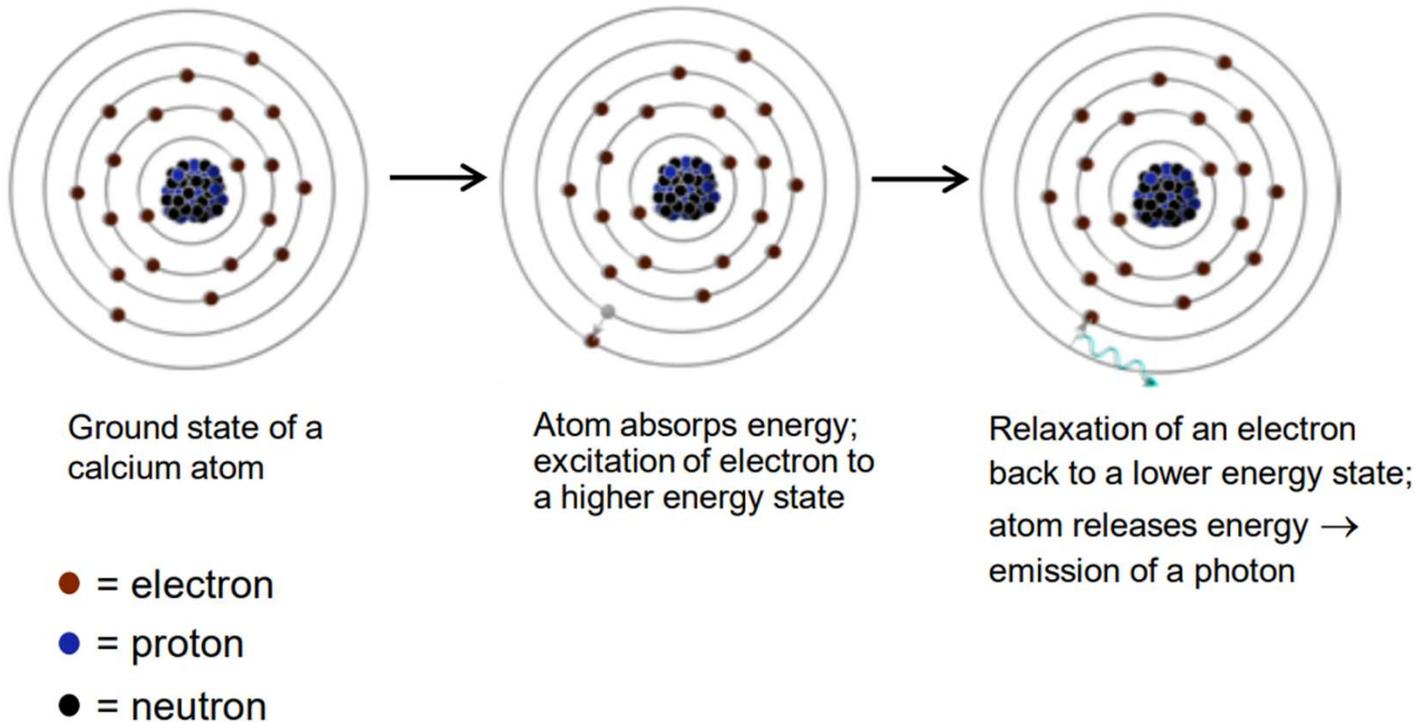


RF glow

Optical Emission Spectroscopy (OES)

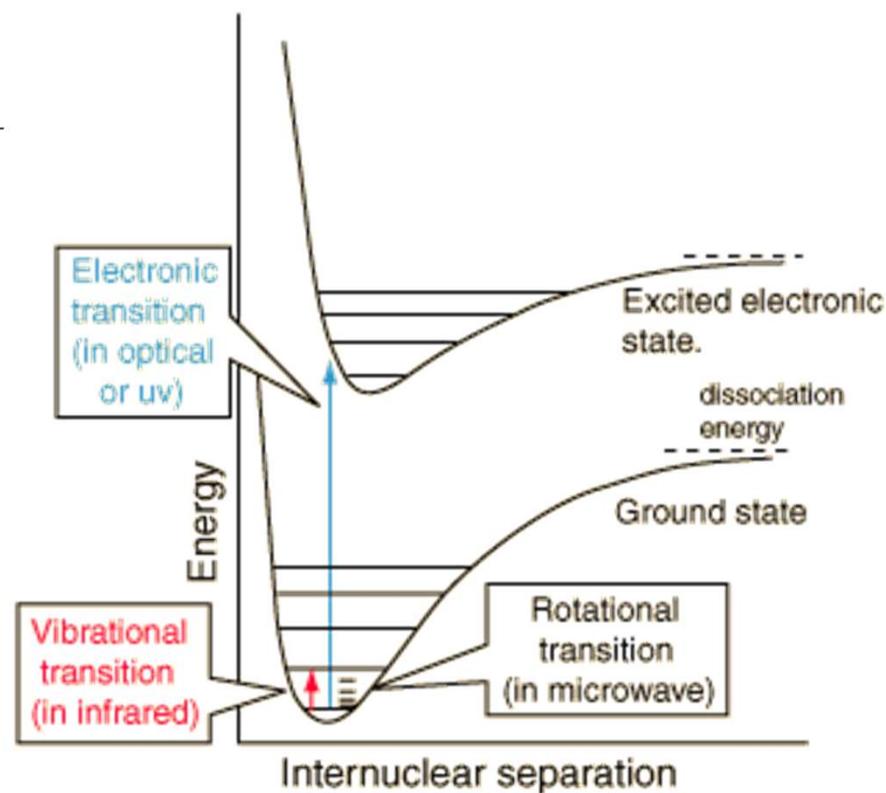
OES is based on the **excitation of particles** (atoms, molecules, ions) and measurement of radiation (light "optical") that is emitted while the particle returns to **the ground state**.

OES working range **200-1200 nm**, or from **6.2 eV to 1.03 eV**.



Atomic Orbital Ionization Energies, eV

Atom	1s	2s	2p	3s	3p
H	13.6				
He	24.5				
Li		5.45			
Be		9.30			
B		14.0	8.30		
C		19.5	10.7		
N		25.5	13.1		
O		32.3	15.9		
F		46.4	18.7		
Ne		48.5	21.5		
Na				5.21	
Mg				7.68	
Al				11.3	5.95
Si				15.0	7.81
P				18.7	10.2
S				20.7	11.7
Cl				25.3	13.8
Ar				29.2	15.9



Nitrogen molecule:

$$W_{\text{rot}} = 2.4 \cdot 10^{-4} \text{ eV},$$

$$W_{\text{vib}} = 0.29 \text{ eV},$$

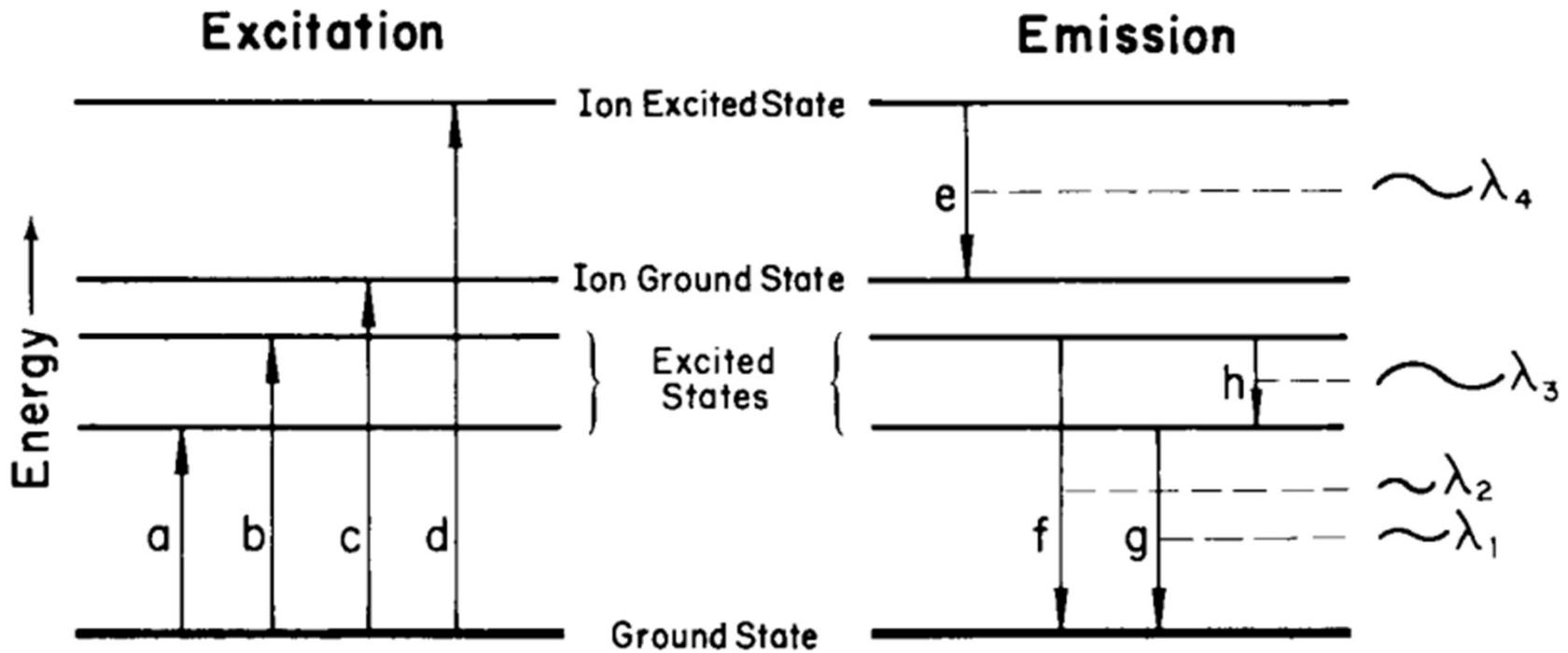
$$W_{\text{elect}} = 6.2 \text{ eV}.$$

Duration of electron collision with molecule: from 10^{-16} to 10^{-15} s

Molecular vibrations have typical time periods of 10^{-14} - 10^{-13} s

Dissociation duration of molecule: 10^{-14} - 10^{-13} s

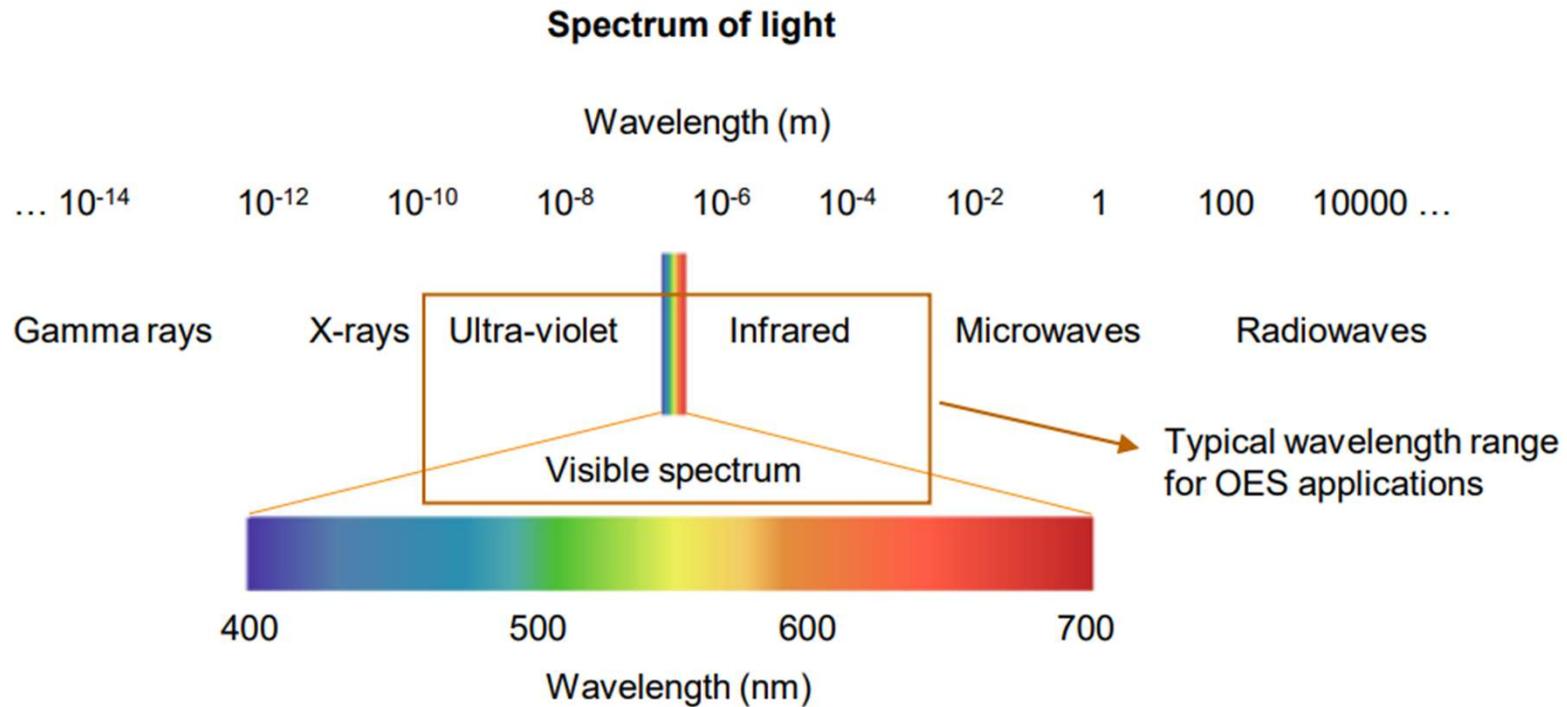
Lifetime of excited particle: 10^{-9} - 10^{-8} s



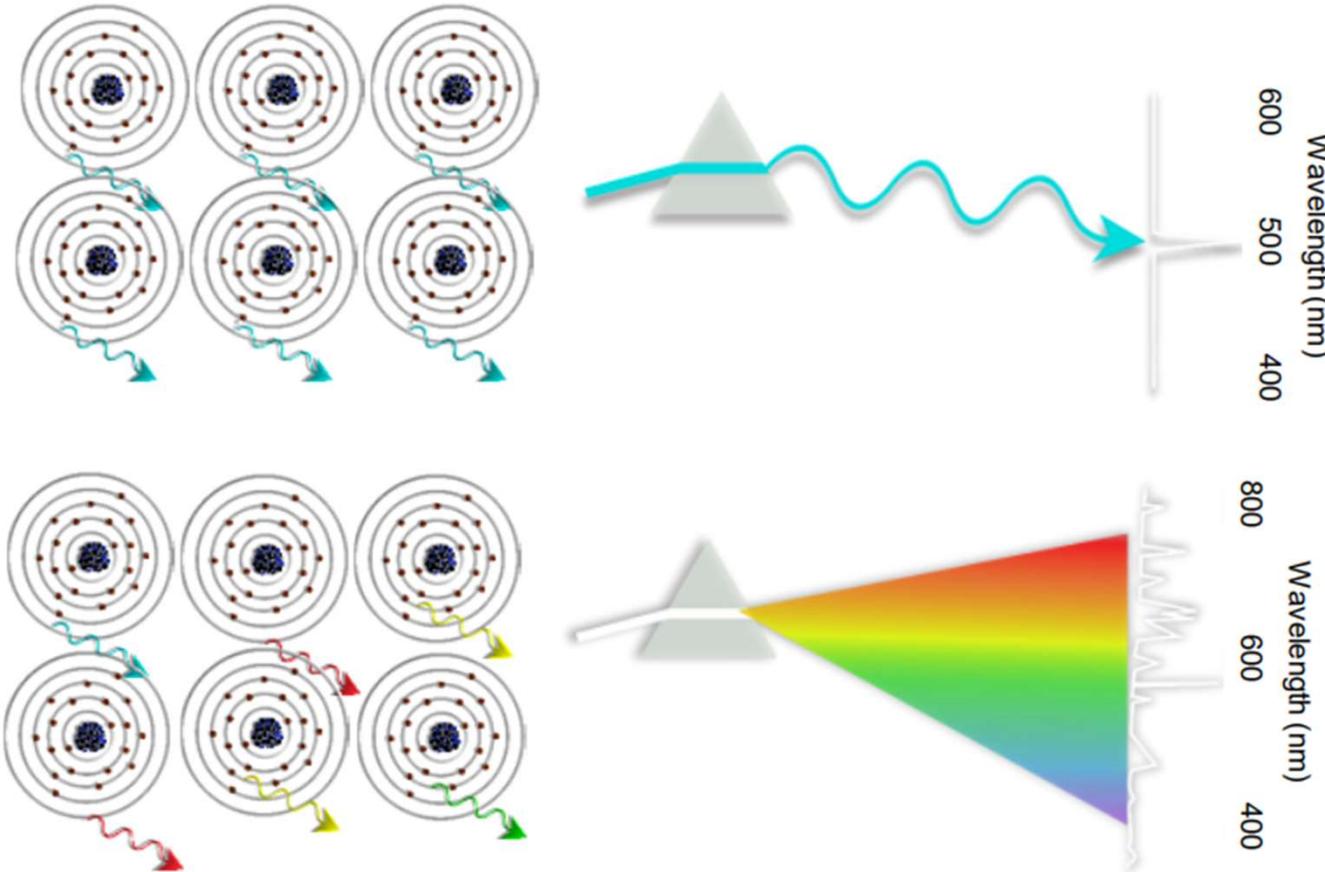
Energy levels diagram depicting energy transitions, **a** and **b** represents **excitation**, **c** is **ionization**, **d** is **ionization/excitation**, **e** is **ion emission**, and **f**, **g**, and **h** are **atom emission**.

Optical Emission Spectroscopy (OES)

- Wavelength of emitted radiation is specific for each particle.
- Qualitative analysis of elements.
- Intensity of emission depends on the amount of atoms/molecules/ions.
- Quantitative analysis of amounts/concentrations.



Optical Emission Spectroscopy (OES)



The wavelengths are separated from one another with a spectrometer

Electrons can transfer also between different energy states

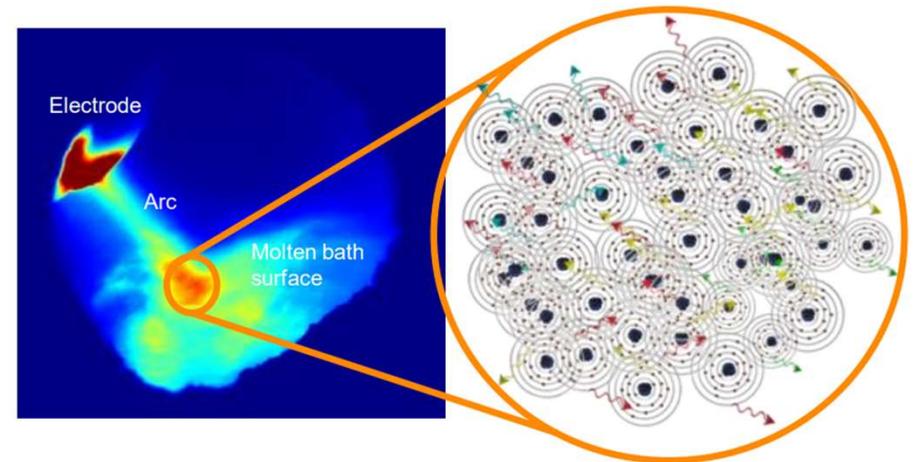
- Every particle has multiple emission lines at different wavelengths
- Atoms, from which the photons have been emitted, can be identified based on these emission lines

Optical Emission Spectroscopy (OES)

Requirements

Separate atomisation/excitation of the sample is required

- ICP-OES = Inductively Coupled Plasma OES
- LA-ICP-OES = Laser Ablation Inductively Coupled Plasma
- SS-OES = Spark Source OES
- MIP-OES = Microwave Induced Plasma OES
- F-OES = Flame OES
- GD-OES = Glow Discharge OES
- RF-GD-OES = Radio Frequency Glow Discharge OES



Different sample requirements for different techniques, e.g.

- Laser-based methods may require smooth sample surfaces for optimal ablation and plasma formation; helps also beam focusing
- GD-OES requires (smooth) solid sample
- SS-OES requires electrical conductivity and smooth surface of solid samples; sample acts as a counter-electrode
- **OES can be used for direct measurement from processes/furnaces in which plasma is formed, plasma discharge, cold plasma in air, etc.**

Optical Emission Spectroscopy(OES)

The most important parameters of a spectrometer are:

- Focal length,
- Diffraction grating,
- Resolution,
- Dispersion,
- Aperture.

The **diffraction grating** is characterized by the grooves per millimeter (lines/mm). Control of the spectral resolution.

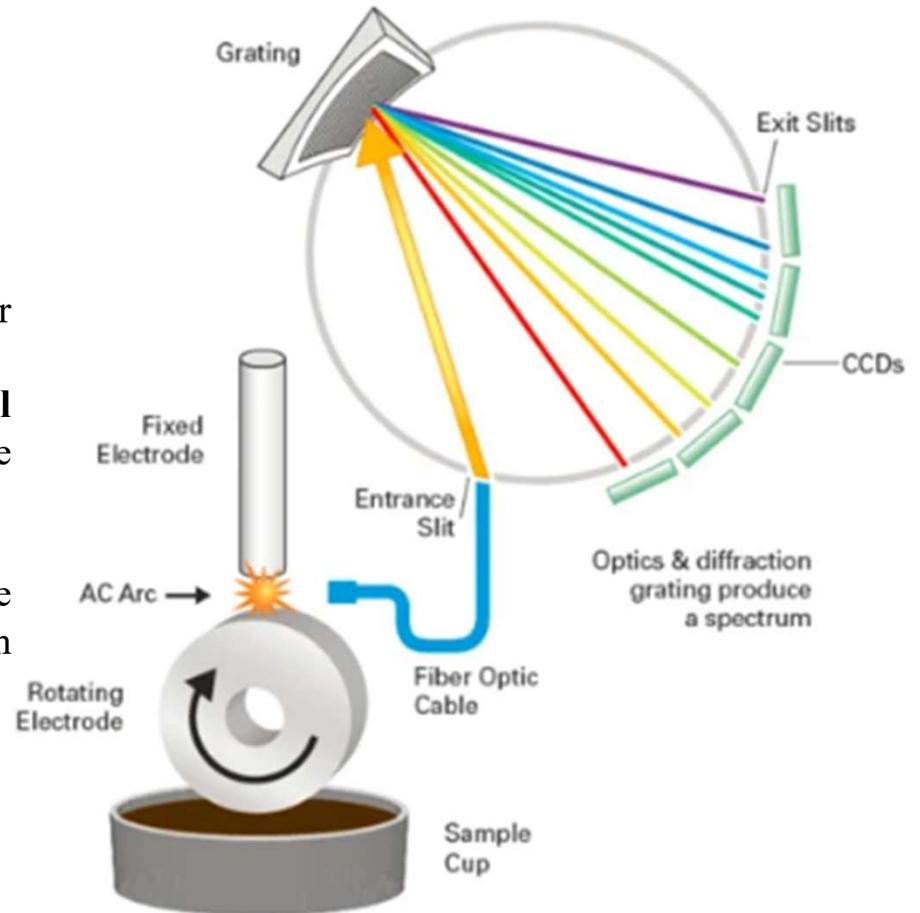
The **focal length** of the spectrometer influences the **spectral resolution** and together with the size of the **grating** defines the **aperture**.

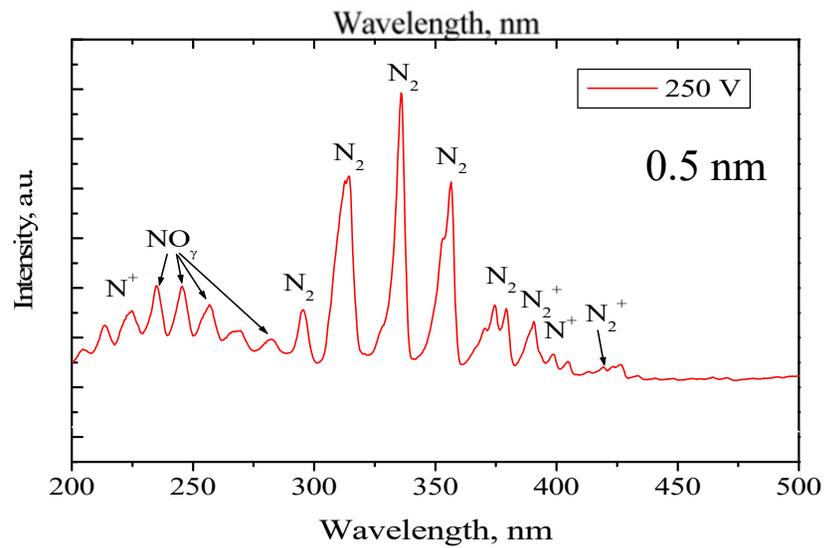
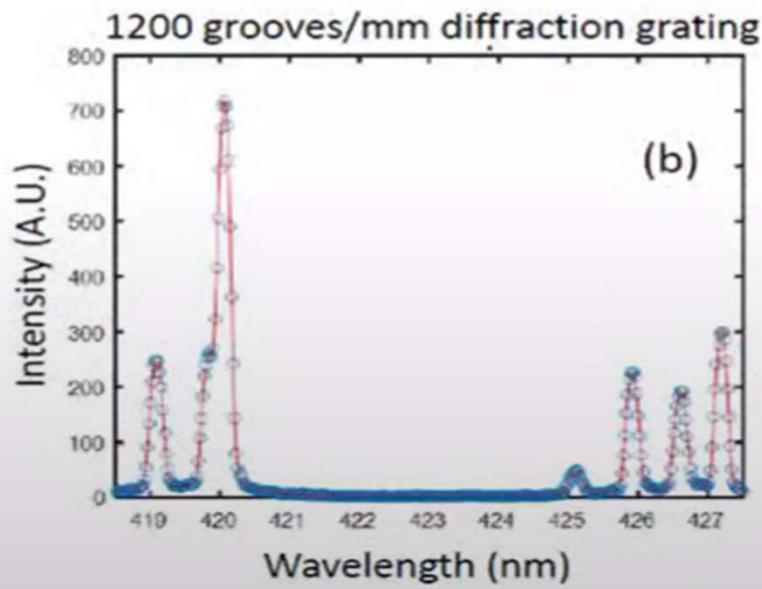
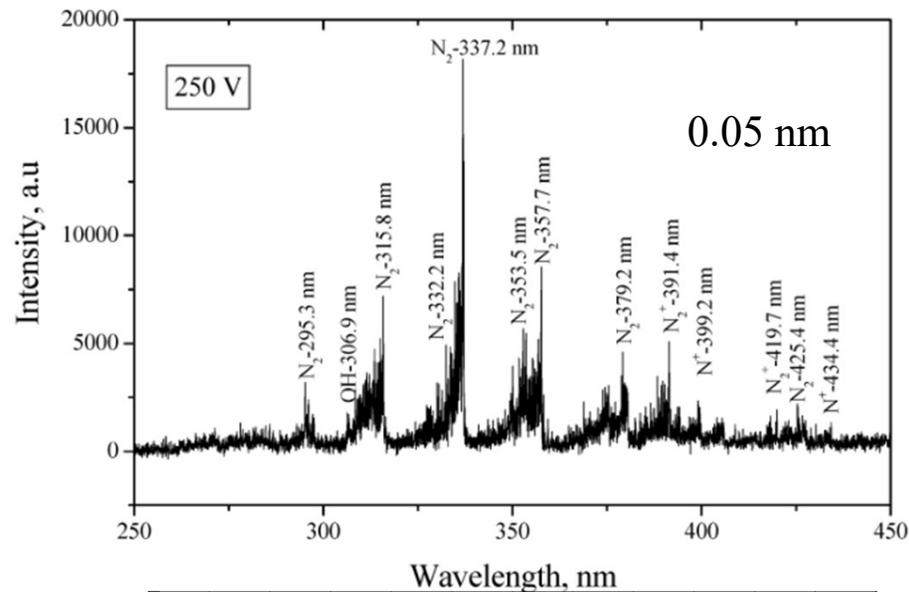
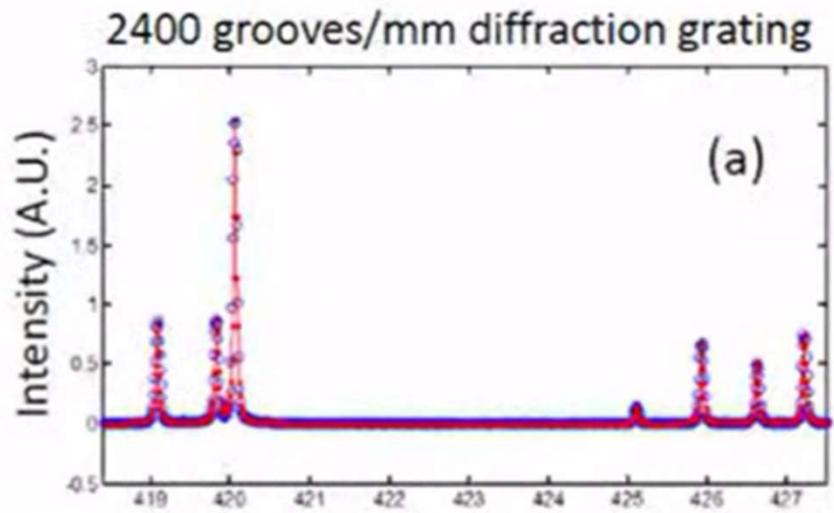
A larger **entrance slit** results in more **intensity**.

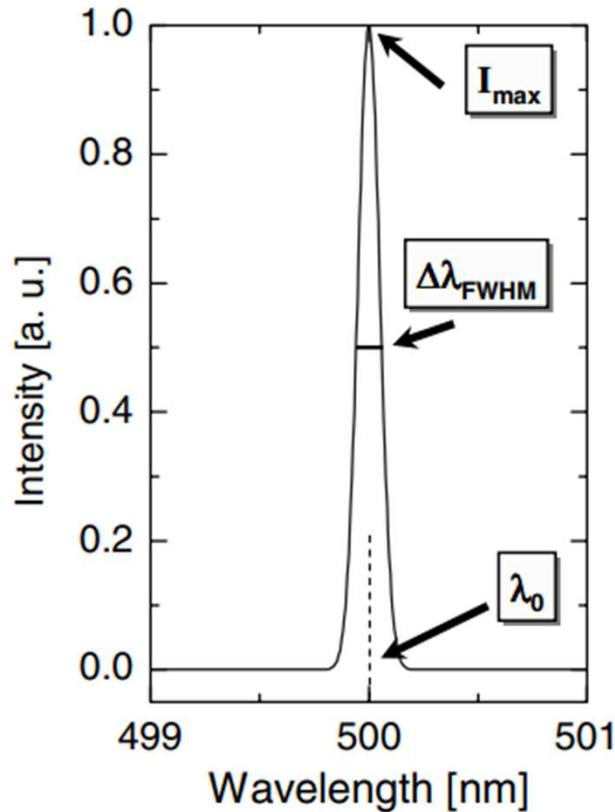
The **width of the exit slit** or the **pixel size** influence the **spectral resolution** of the system. The sensitivity of the system is strongly dominated by the type of detector.

Poor spectral resolution λ is $1 \div 2$ nm.

An excellent spectral resolution λ is $1 \div 2$ pm.







Line radiation and its characteristics.

The central wavelength of line emission λ_0 is given by the photon energy:

$$E = E_p - E_k \quad (1)$$

Planck constant h , speed of light c .

$$\lambda_0 = h c / (E_p - E_k) \quad (2)$$

The central wavelength is an identifier for the radiating particle.

The line intensity is quantified by the line emission coefficient:

$$\varepsilon_{pk} = n(p) A_{pk} \frac{h c}{4\pi \lambda_0} = \int_{\text{line}} \varepsilon_\lambda d\lambda \quad (3)$$

in units of $\text{W (m}^2 \text{ sr)}^{-1}$, where 4π represents the solid angle d (isotropic radiation), measured in steradian (sr), the transition probability A_{pk} , the particle density in the excited state $n(p)$.

The line profile P_λ correlates the line emission coefficient ($\varepsilon_{p\lambda}$) with the spectral line emission coefficient ε_λ

$$\varepsilon_\lambda = \varepsilon_{pk} P_\lambda \quad \text{with} \quad \int_{\text{line}} P_\lambda d\lambda = 1. \quad (4)$$

A characteristic of the line profile is the full width at half maximum (FWHM) of the intensity, λ_{FWHM} .

The line profile depends on the broadening mechanisms.

The line width correlates with the particle temperature.

The absolute line intensity in units of photons $(\text{m}^3 \text{s})^{-1}$.

$$I_{pk} = n(p) A_{pk} \quad (5)$$

$$I_{pk} = n_n n_e X_{pk}^{\text{eff}}(T_e, n_e, \dots). \quad (6)$$

The line intensity depends only on the population density of the excited level $n(p)$ which, depends strongly on the plasma parameters $n(p) = f(T_e, n_e, T_n, n_n, \dots)$, X_{pk}^{eff} is the effective emission rate coefficient.

Particles temperature and densities in the plasma:

$$\frac{I_{pk}^1}{I_{lm}^2} = \frac{n_1 X_{pk}^{\text{eff}}(T_e, n_e, \dots)}{n_2 X_{lm}^{\text{eff}}(T_e, n_e, \dots)} \quad (7)$$

Threshold energies, cross section values, statistic weight factors, emission rate coefficients etc. are required for the theoretical calculation.

Balmer Series for hydrogen atom

Line	Wavelength [\AA]
H _{α}	6562.79
H _{β}	4861.33
H _{γ}	4340.47
H _{δ}	4101.74
H _{ϵ}	3970.07
H _{ζ}	3889.05
H _{η}	3835.39
H _{θ}	3797.90
H _{ι}	377.63

Line broadening mechanisms

Broadening due particle collisions

Broadening Type	Collisions between
Resonance	Identical particles
Van der Waals	Different neutral particles
Stark	Charged Particles

Broadening due other reasons

Broadening Type	Due to:
Natural	Results from Heisenberg uncertainty principle
Instrumental	Results from measuring spectrometer which has a finite resolution
Doppler	Difference in speed of particles

FWHM (Full width at half maximum) of the Lorentzian ($\Delta\lambda_L$) and Gaussian ($\Delta\lambda_G$) component respectively.

$$\Delta\lambda_G = \sqrt{(\Delta\lambda_D)^2 + (\Delta\lambda_{INST})^2} \text{ [Å]} \quad (1)$$

$$\Delta\lambda_L = \Delta\lambda_S + \Delta\lambda_W + \Delta\lambda_R + \Delta\lambda_{NAT} \quad (2)$$

Instrumental Broadening

$$\Delta\lambda_{INST} = (6.5 \times 10^{-3})f \text{ [Å]} \quad (3)$$

Where f is the width of the slits in μm .

Doppler Broadening

$$\Delta\lambda_D = 7.16 \times 10^{-7} \lambda_0 \sqrt{\frac{T}{M}} \text{ [Å]} \quad (4)$$

Due the thermal velocity of the emitting atoms.

Where M is the mass of the radiating atom in atomic mass units, λ_0 is the central wavelength in nm and T the temperature of the radiating atoms which in some cases may be equal to the gas temperature.

Natural Broadening

$$\Delta\lambda_{NAT} = \frac{\tau}{4\pi c} \text{ [Å]} \quad (5)$$

The natural broadening is caused by the finite lifetime of excited states and also can be determined by Heisenberg's uncertainty relation. ($\sim 10^{-3}$)

Stark Broadening

$$\Delta\lambda_S = 2.50 \times 10^{-9} \alpha_1 n_e^{\frac{2}{3}} \text{ [Å]} \quad (6)$$

This broadening is caused by Coulomb interactions between the charged particles present in plasma.

$$\text{Where } \alpha_{\frac{1}{2}} = 0.0783 \text{ [Å/cgs]}$$

Resonance Broadening

This broadening is caused by the interaction of the emitting atoms with atoms in ground state.

$$\Delta\lambda_R = \frac{3e^2\lambda_{42}^2}{16\pi^2\varepsilon_0m_e c^2} \left\{ \lambda_{21}f_{12} \sqrt{\frac{g_1}{g_2}} N_g + \lambda_{41}f_{14} \sqrt{\frac{g_1}{g_4}} N_g + \lambda_{42}f_{42} \sqrt{\frac{g_2}{g_4}} N_g \right\} [\text{\AA}] \quad (7)$$

λ_{21}	121.567nm
λ_{41}	97.2537nm
g_1	2
g_2	8
g_4	32
f_{12}	0.4162
f_{14}	0.02899
f_{24}	0.1193

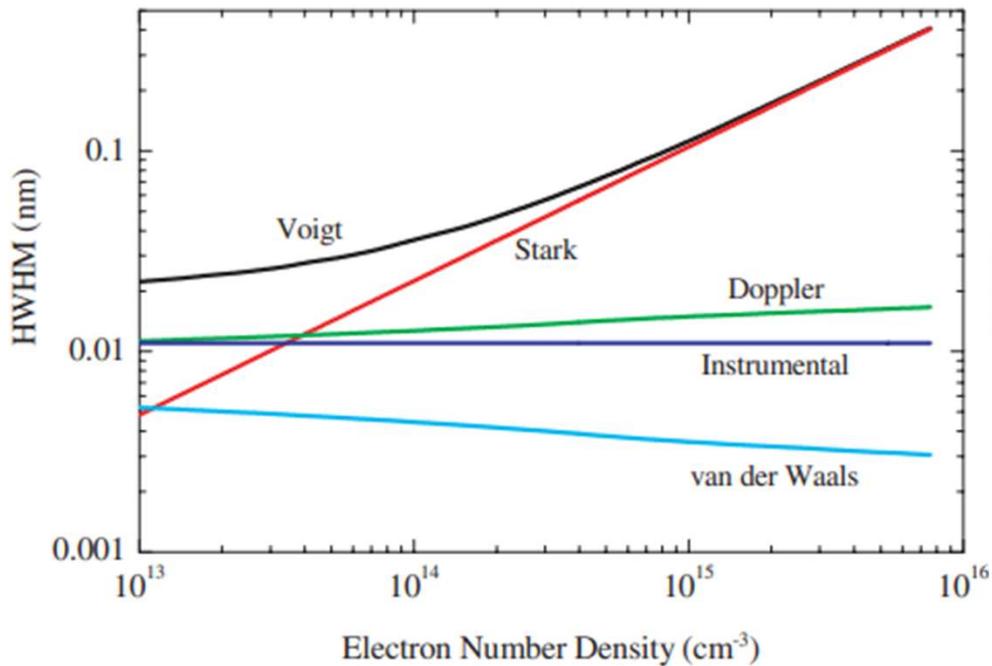
$$\Delta\lambda_R = 30.6 \frac{X_h}{T_g} [\text{\AA}] \quad (8)$$

The hydrogen atoms mole fraction X_h and the gas temperature T_g .

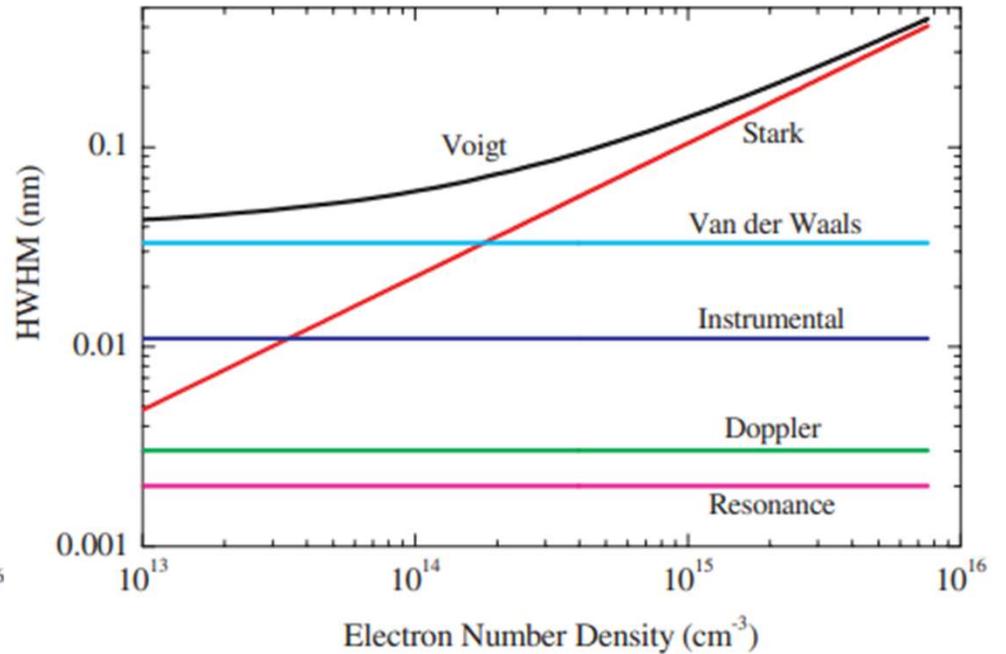
Van der Waals Broadening

$$\Delta\lambda_W = \frac{\lambda_{42}^2}{2c} \left[\frac{9\pi^5 \overline{R_\alpha^2}}{16m_e^3 E_p^2} \right]^{\frac{2}{5}} \overline{V_{rp}^{3/5}} N_p [\text{\AA}] \quad (9)$$

Where $\overline{V_{rp}^{3/5}}$ is the relative speed of the radiating atom and the perturber, E_p is the energy of the first excited state of the perturber connected with its ground state by an allowed transition, and $\overline{R_\alpha^2}$ is a matrix element.



H_β lineshape broadening as a function of the electron number density in LTE air at atmospheric pressure.



H_β lineshape broadening as a function of the electron number density in nonequilibrium atmospheric pressure air at a gas temperature of 300 K.

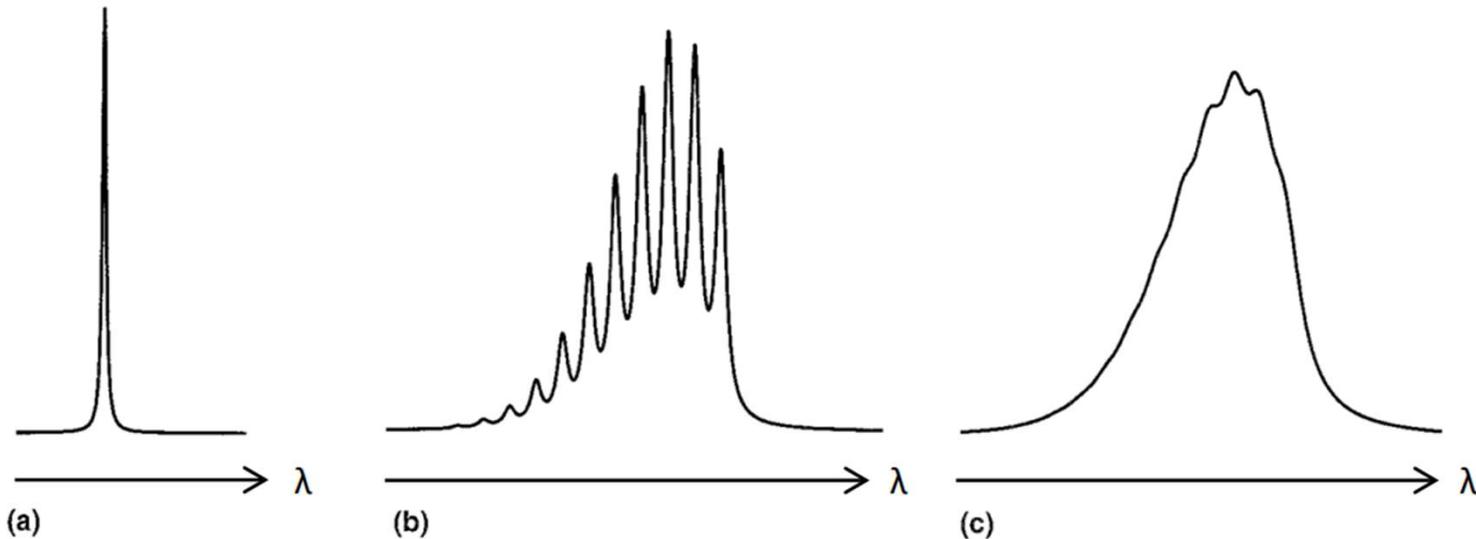
Electron Temperature

$$T = M \left(\frac{\Delta\lambda_D}{(7.16 \times 10^{-7})(\lambda)} \right)^2 [K] \quad (10)$$

Density of electron

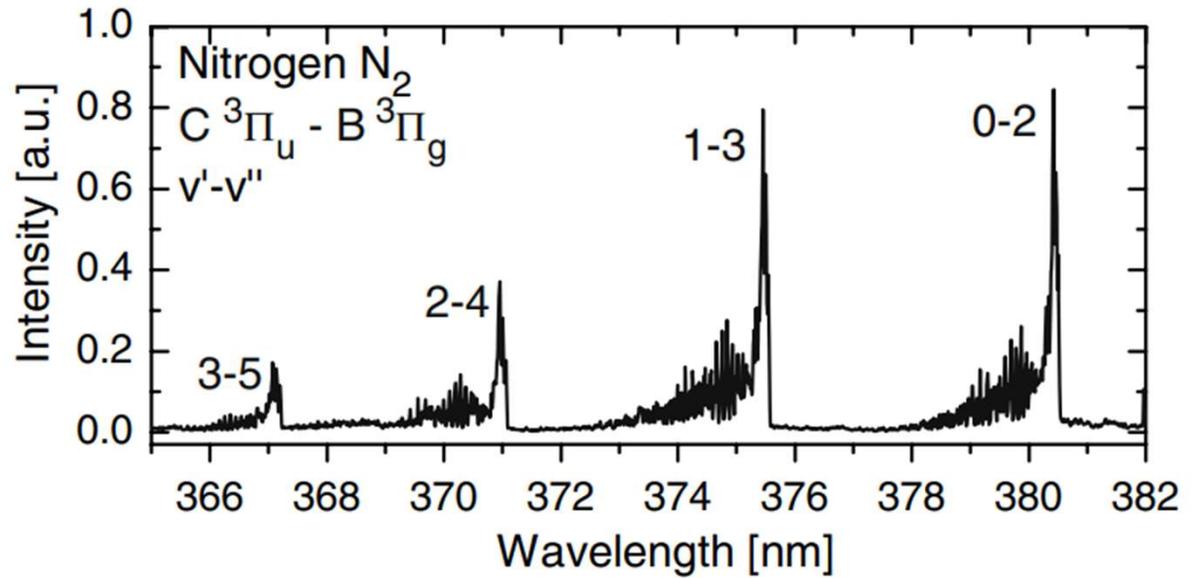
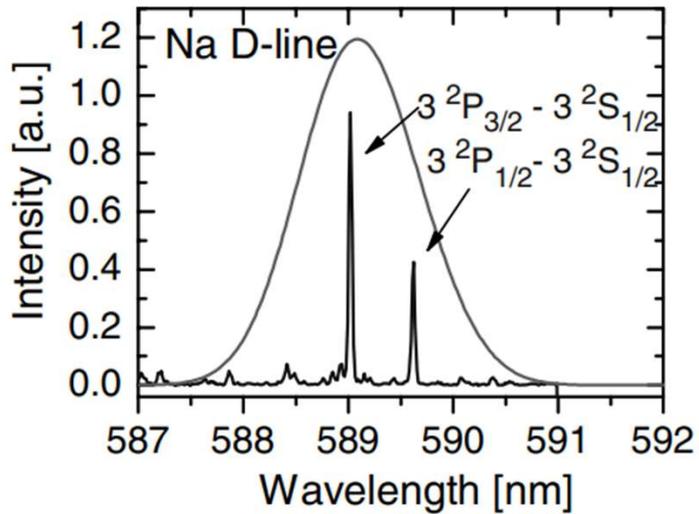
$$n_e = \left(\frac{\Delta\lambda_S}{(2.5 \times 10^{-9})(\alpha_1)^{\frac{1}{2}}} \right)^{3/2} [cm^3] \quad (11)$$

A schematic spectrum is shown for an atom (a), for a small polyatomic molecule (b) and a large polyatomic molecule (c)



Larger molecules also have a larger moment of inertia, which leads to closely spaced rotational levels. In that case, the spectral lines overlap and contribute to a broader band in the spectrum.

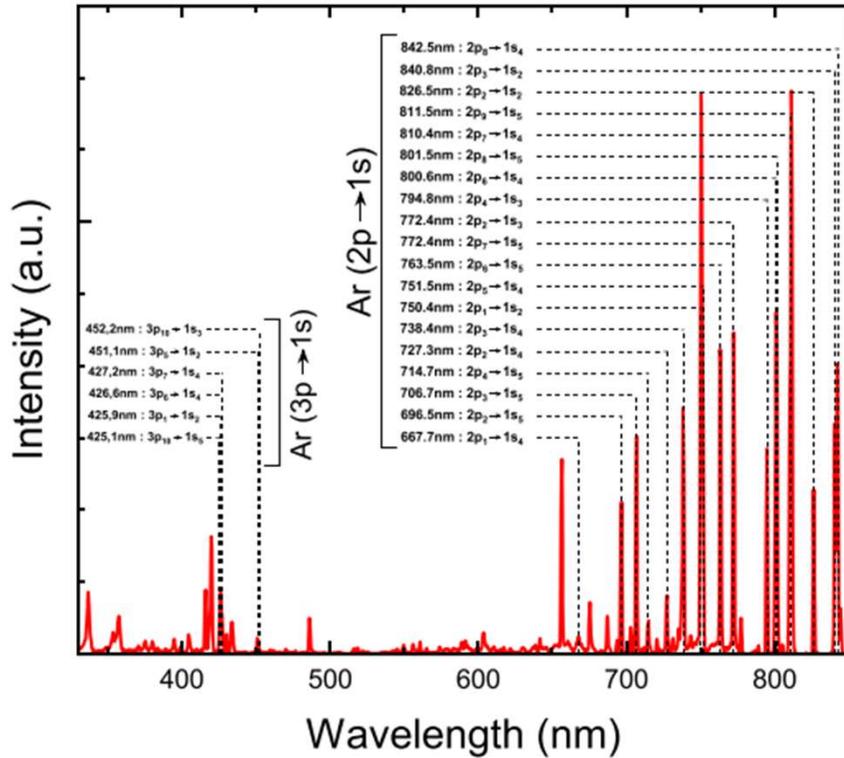
The collision of one molecule with another can affect the energy of the emitted photon and thereby create a broader band in the emission spectrum.



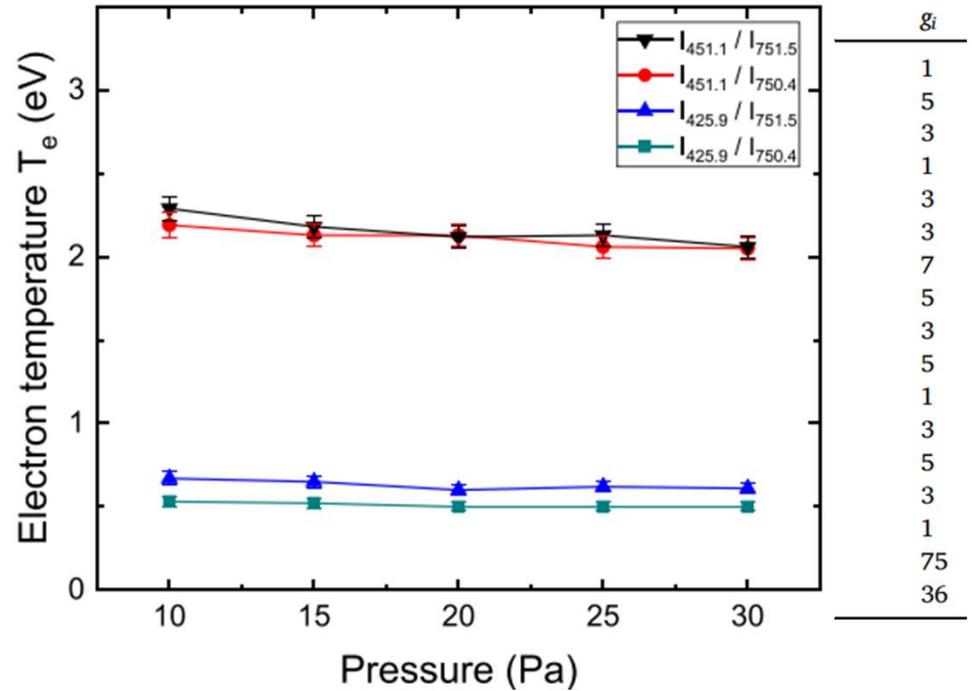
Atomic and molecular spectra: NaD-lines and vibrational bands of the second positive system of N_2 .

The two narrow lines correspond to a recorded spectrum where the fine structure is resolved, whereas the broad line would be observed by a spectrometer with poor spectral resolution.

OES spectra of the argon plasma



Argon excitation energy thresholds and statistical weights

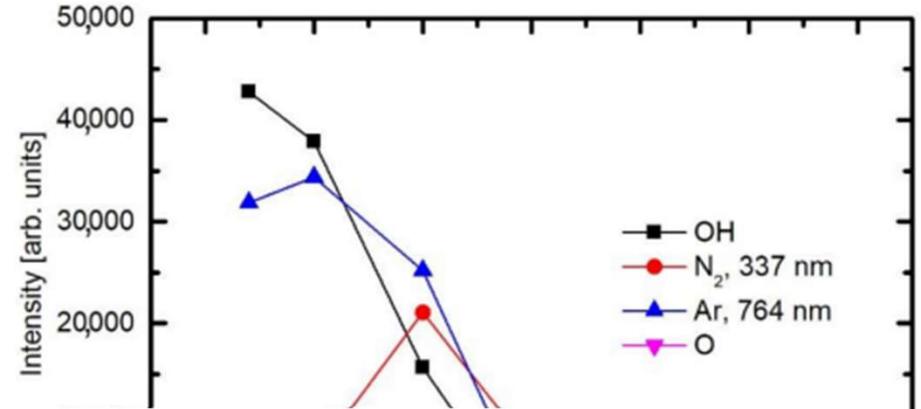
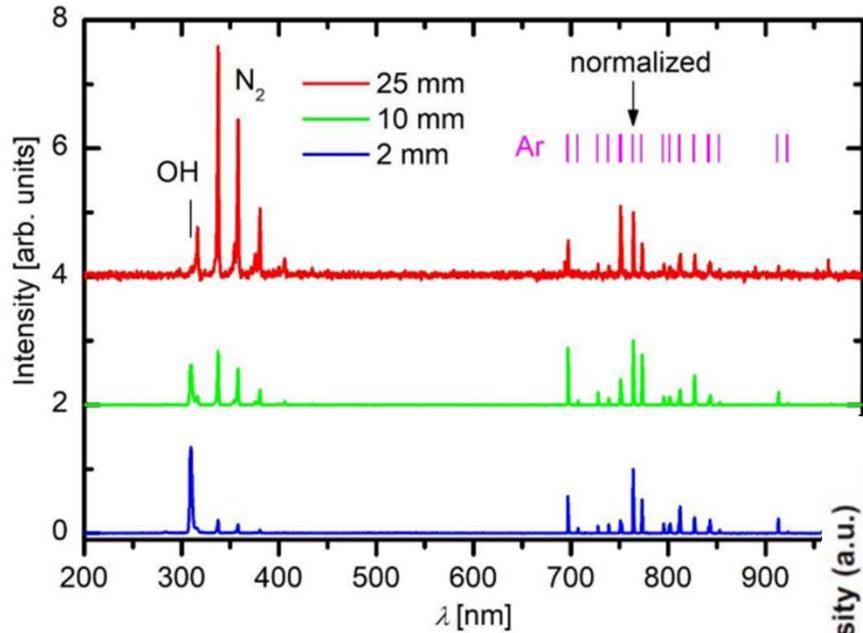


g_i
1
5
3
1
3
3
7
5
3
5
1
3
5
1
3
1
75
36

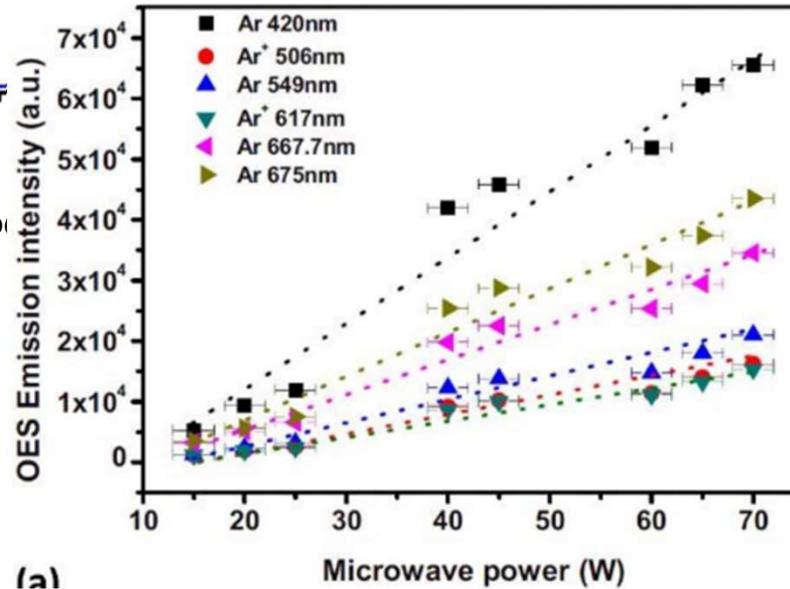
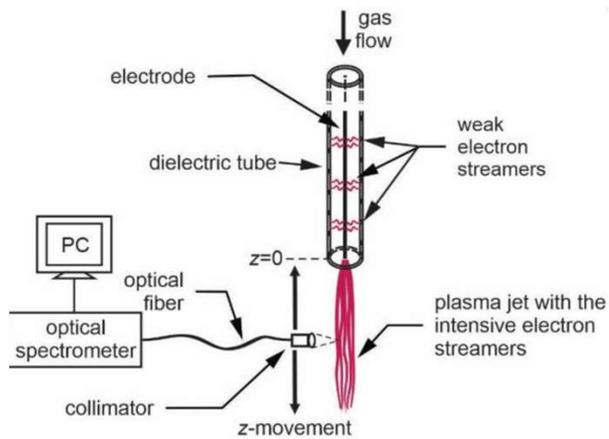
Electron temperature

$$R(T_e) = \frac{I_{w2}}{I_{w1}} = \frac{\int_{E_k}^{\infty} \sigma_{Opt}^{3p_k \rightarrow 1s_1}(E) e^{-\frac{E}{k_B T_e}} dE}{\int_{E_i}^{\infty} \sigma_{Opt}^{2p_i \rightarrow 1s_j}(E) e^{-\frac{E}{k_B T_e}} dE}$$

Optical emission spectra of the argon plasma

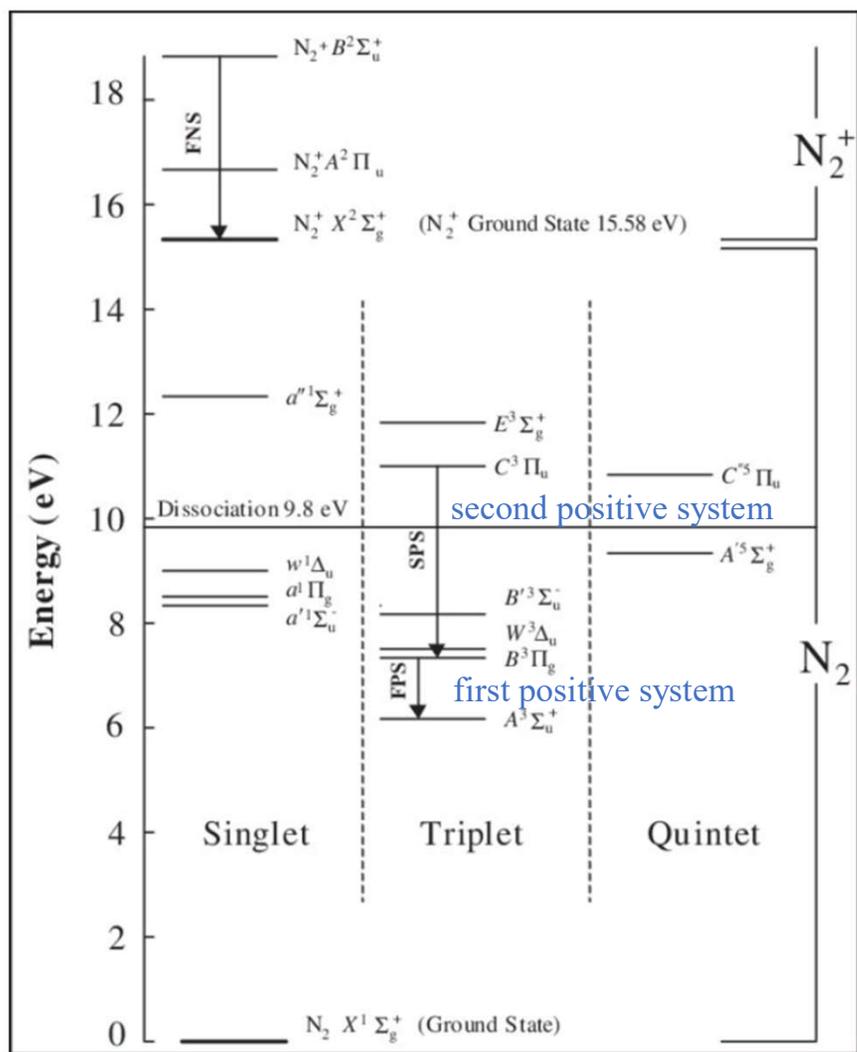


The OES sp

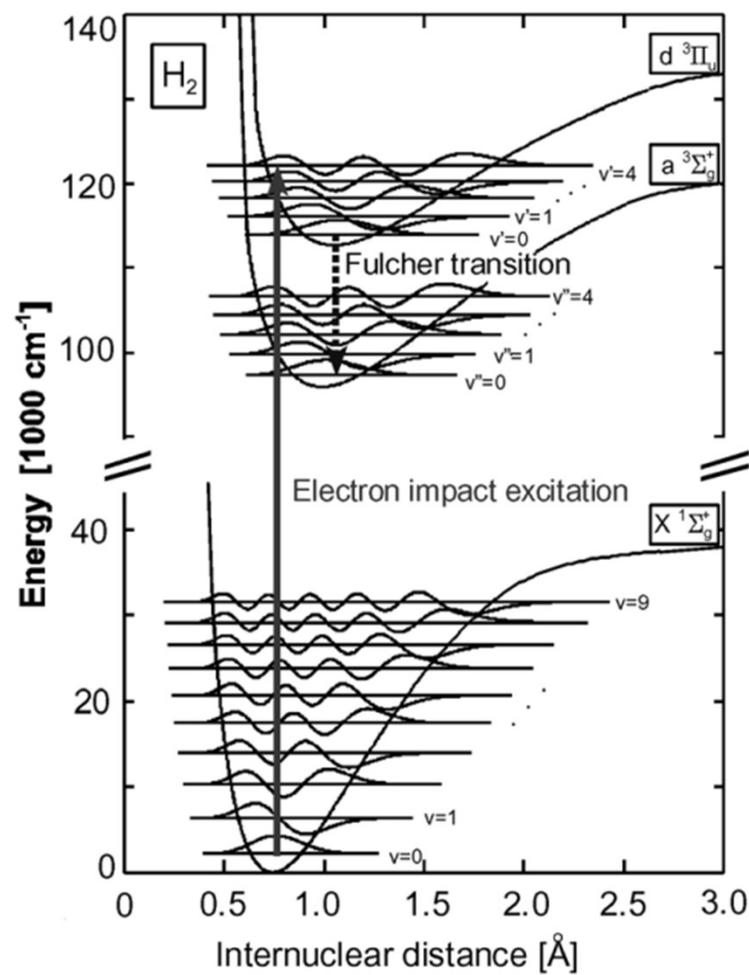


(a)

n the discharge tube

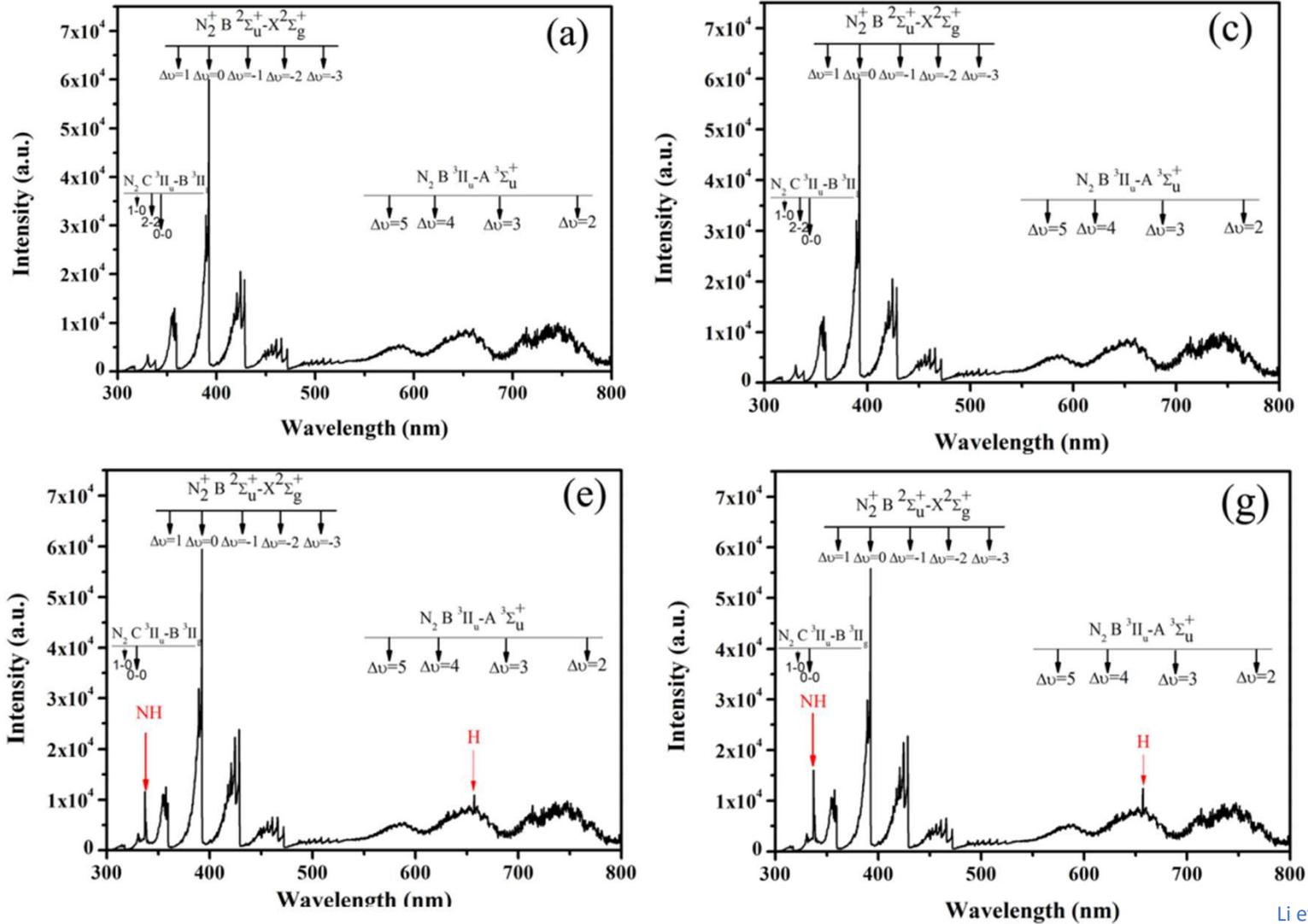


Example of an energy level diagram of a nitrogen molecule.

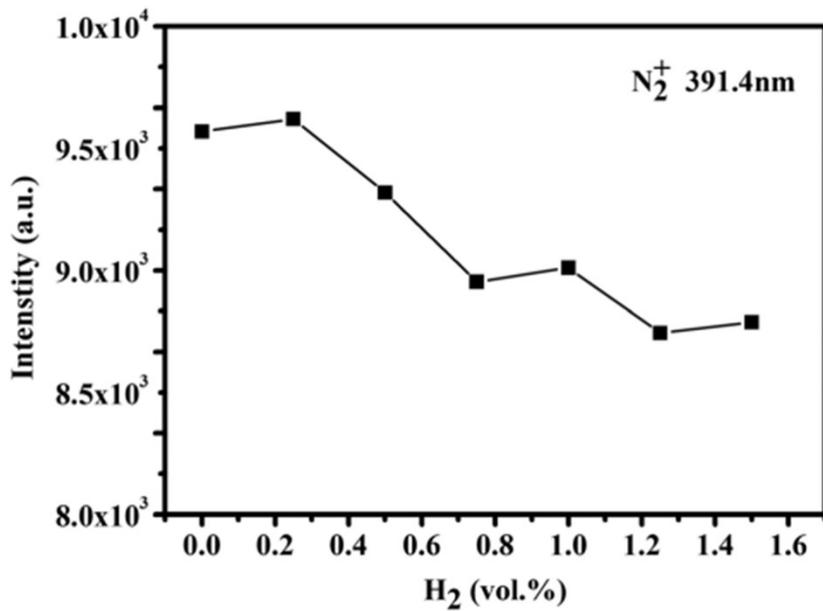


Molecular excitation and radiation according to the Franck–Condon principle for the ground state and two excited states of molecular hydrogen

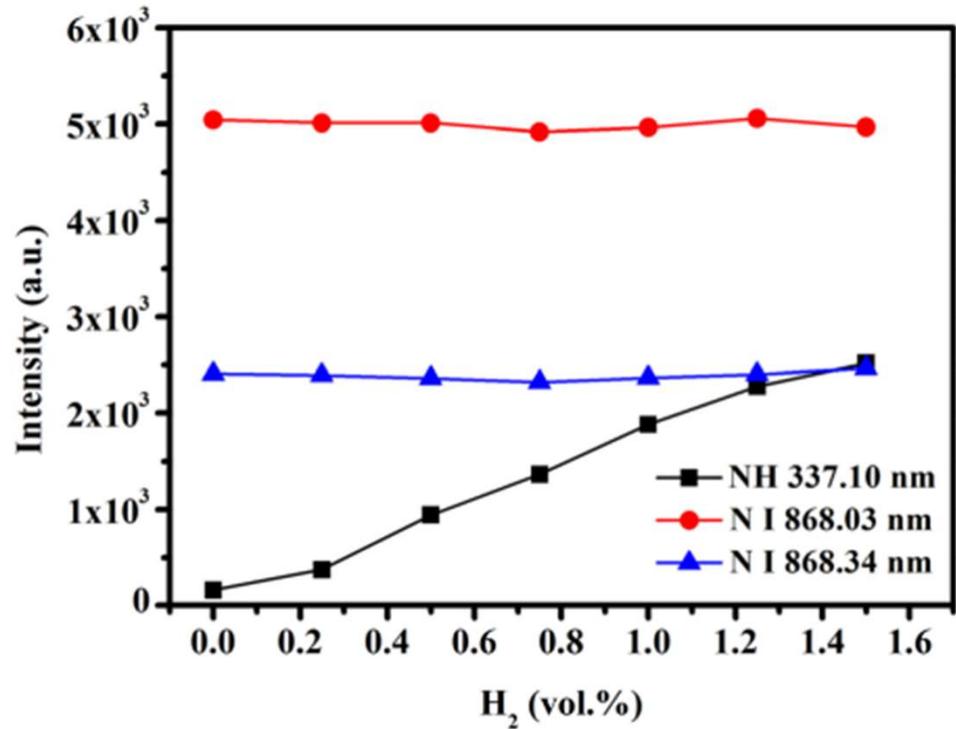
Typical emission spectra of the nitrogen plasma



Optical emission spectra for N_2 gas at different mixture ratios of H_2 : (a) 0 vol. %, (c) 0.5 vol. %, (e) 1 vol. %, (g) 1.5 vol. %

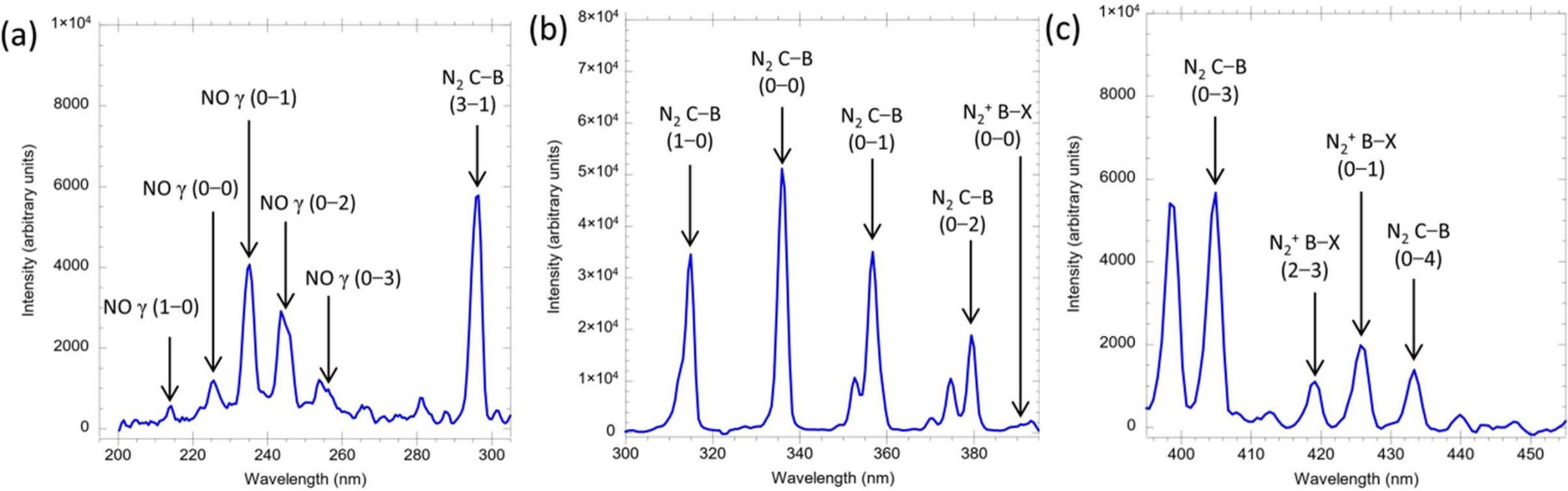


Dependence of the intensity of N₂⁺ first negative band head at 391.4 nm on the mixture ratio of H₂



The spectral emission intensities of NH radial (337.10 nm), nitrogen atom (868.03 nm) and nitrogen atom (868.34 nm) with the mixture ratio of H₂.

Typical emission spectra of the air plasma



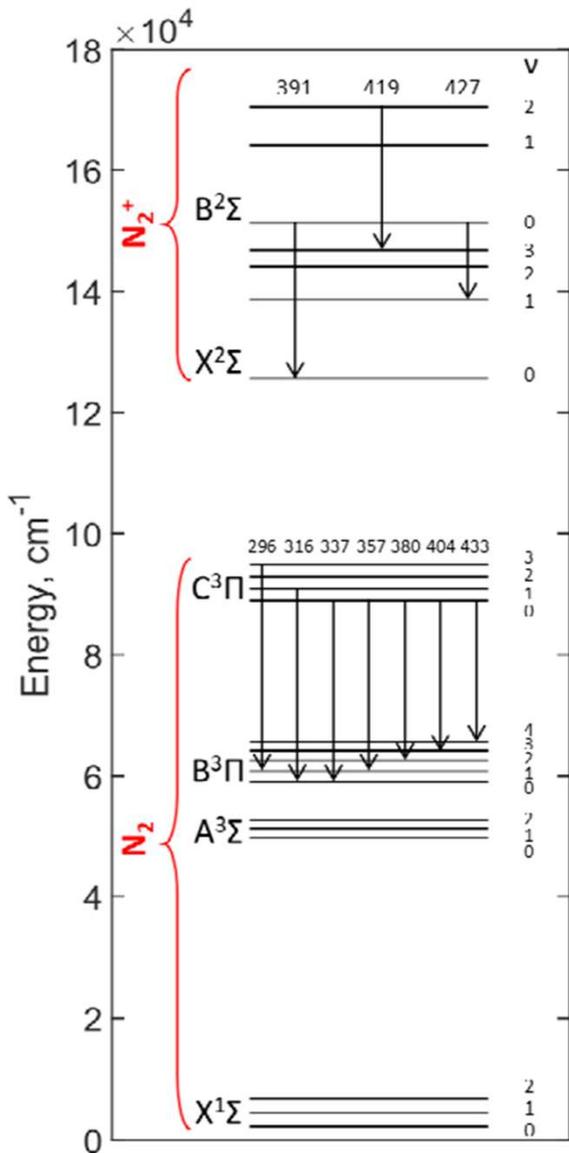
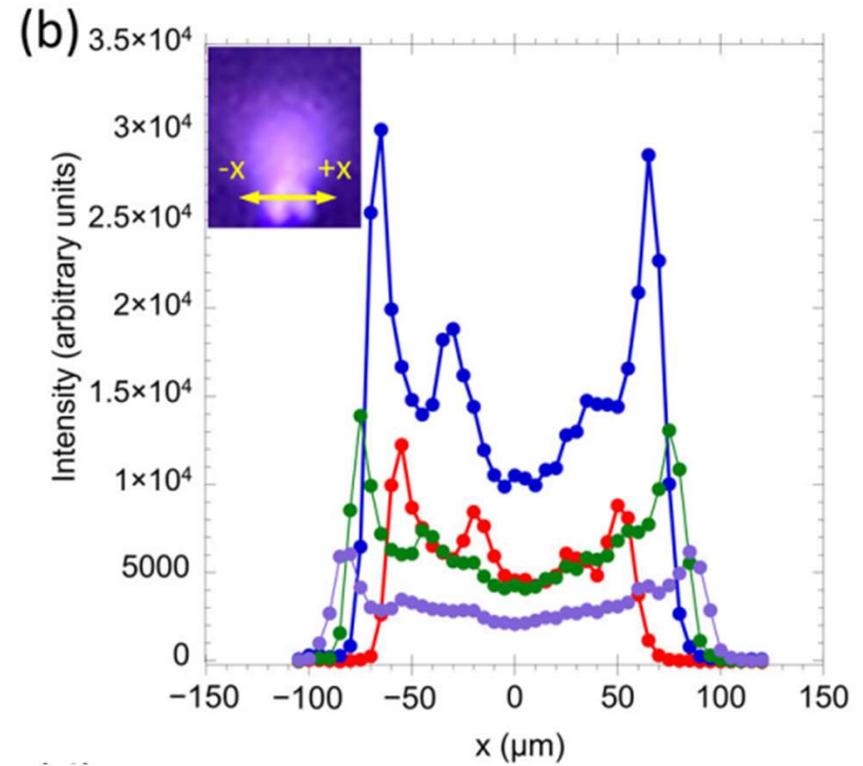
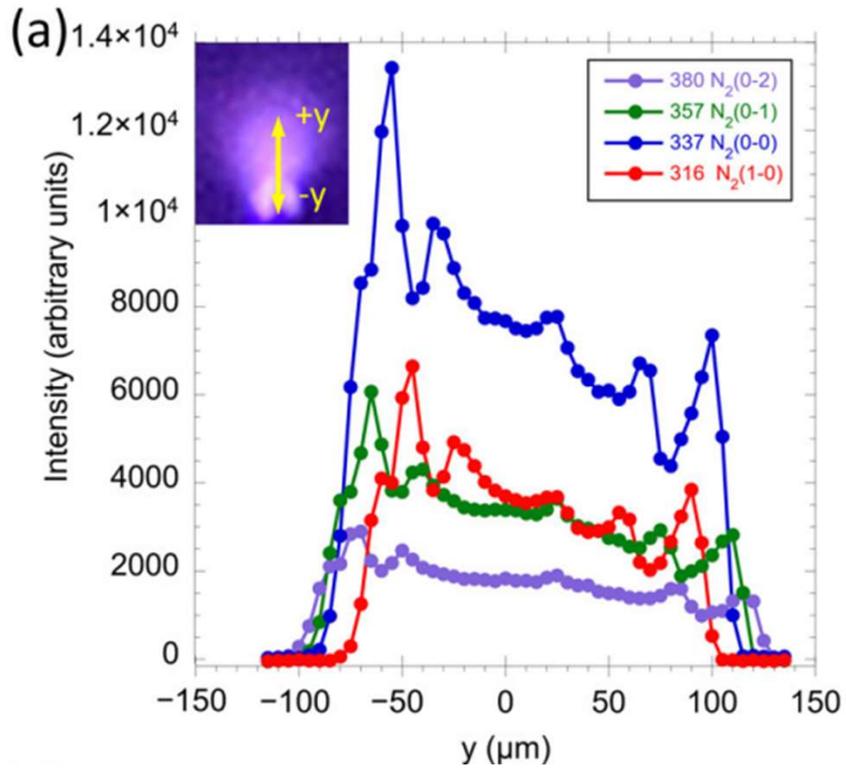


Table 1. Summary of the N_2 , N_2^+ , and NO transitions and their corresponding emission wavelengths and Franck-Condon factors [30].

	Transition Band	Wavelength (nm)	Franck-Condon Factor
NO- γ ($A^2\Sigma-X^2\Pi$)	1-0	214	0.330
	0-0	226	0.162
	0-1	235	0.262
	0-2	245	0.237
	0-3	256	0.161
N_2 ($C^3\Pi-B^3\Pi$)	3-1	296	0.252
	1-0	316	0.388
	0-0	337	0.455
	0-1	357	0.331
	0-2	380	0.145
	0-3	404	0.0494
	0-4	433	0.0145
N_2^+ ($B^2\Sigma-X^2\Sigma$)	0-0	391	0.651
	2-3	419	0.229
	0-1	427	0.259

Part of the bands of N_2^+ ($B^2\Sigma-X^2\Sigma$) and N_2 second positive system ($C^3\Pi-B^3\Pi$) vibrational excitation.

The signal intensity of the N₂ second positive system (C³Π–B³Π) along with the (a) y, (b) x directions.



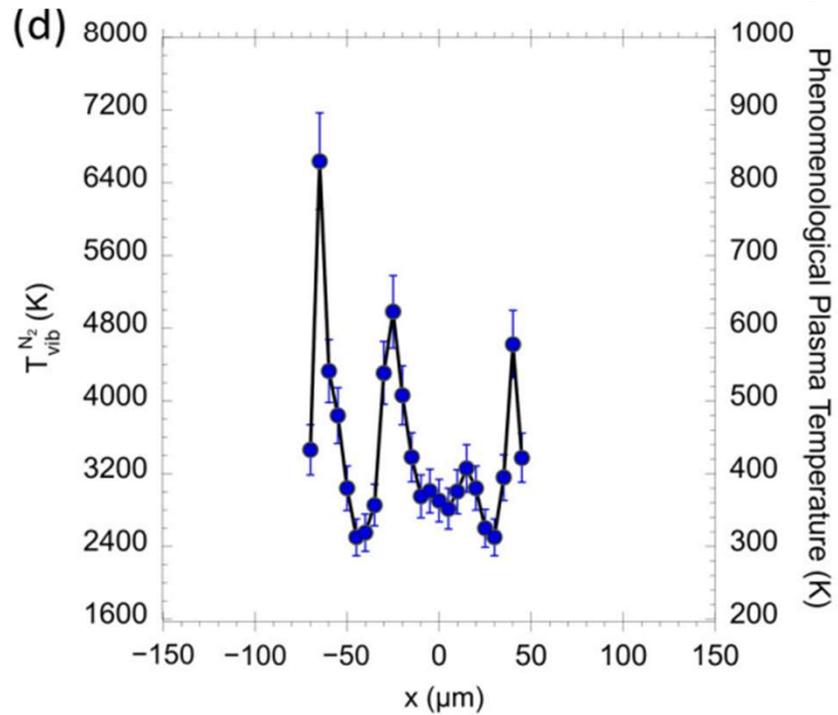
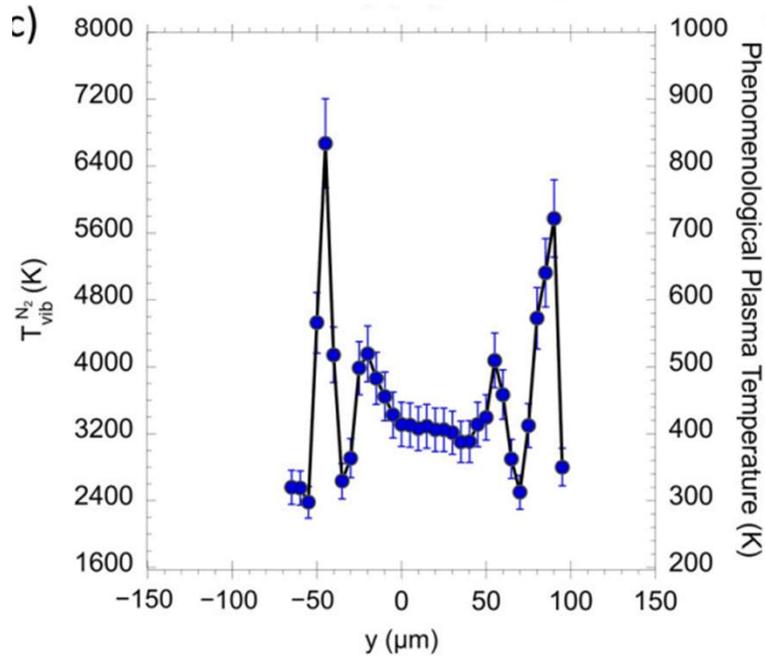
Temperature for $v = 0$ and $v = 1$ in the N_2 second positive system ($C^3\Pi-B^3\Pi$):

$$T_{N_2}^{vib} = \frac{E_{v_2} - E_{v_1}}{k_B} \left[\ln \left(\frac{I_{\lambda_1} \lambda_1^4 FCF_{\lambda_2}}{I_{\lambda_2} \lambda_2^4 FCF_{\lambda_1}} \right) \right]^{-1} \quad (1)$$

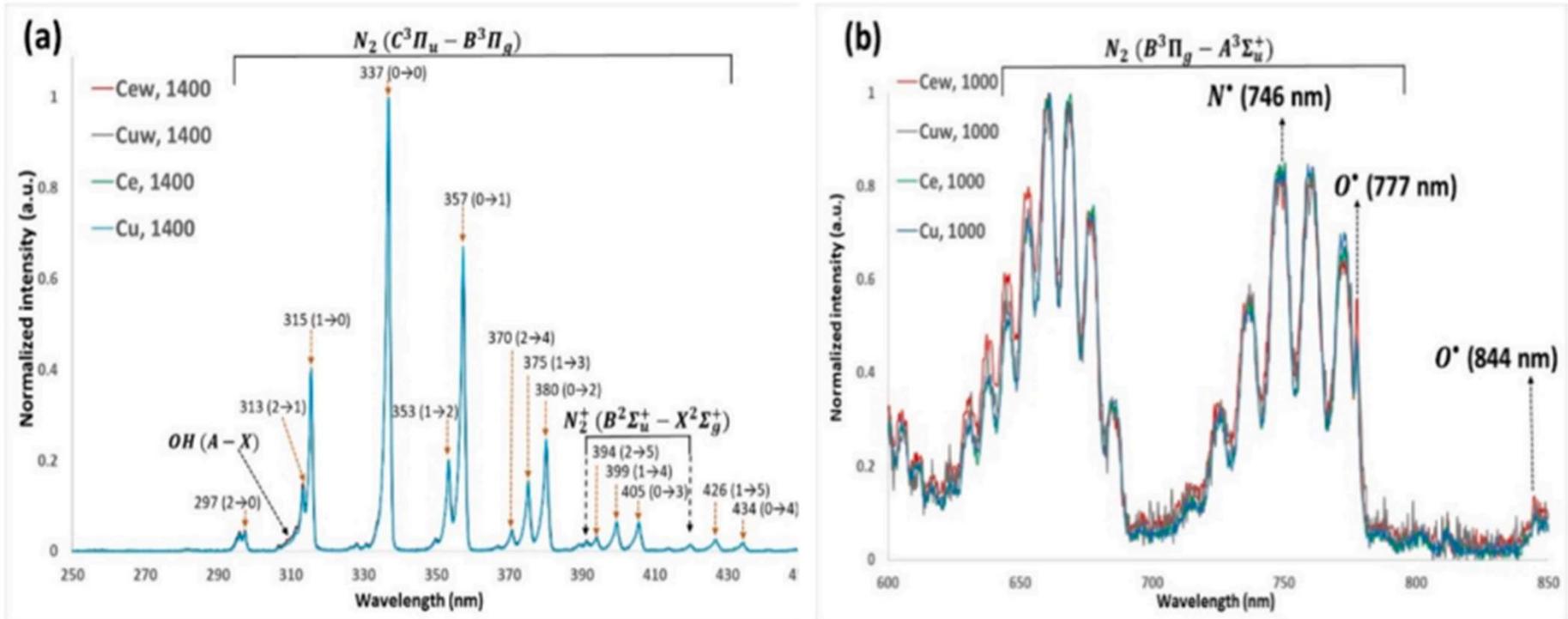
where I_{λ_1} and I_{λ_2} are the emission intensities of the transitions at λ_1 and λ_2 ; E_{v_1} and E_{v_2} are the energy of the upper energy levels; FCF is the Frank–Condon factor.

$$T_{N_2}^{vib} = \frac{2785}{0.11 + \ln \left(\frac{I_{\lambda=337}}{I_{\lambda=316}} \right)} \quad (2)$$

$\lambda_1, \lambda_2, E_{v_1}, E_{v_2}, FCF_{\lambda_1}$ and FCF_{λ_2} , namely **337 nm, 316 nm, 88.957 cm⁻¹, 90.893 cm⁻¹, 0.455, and 0.388**, respectively,

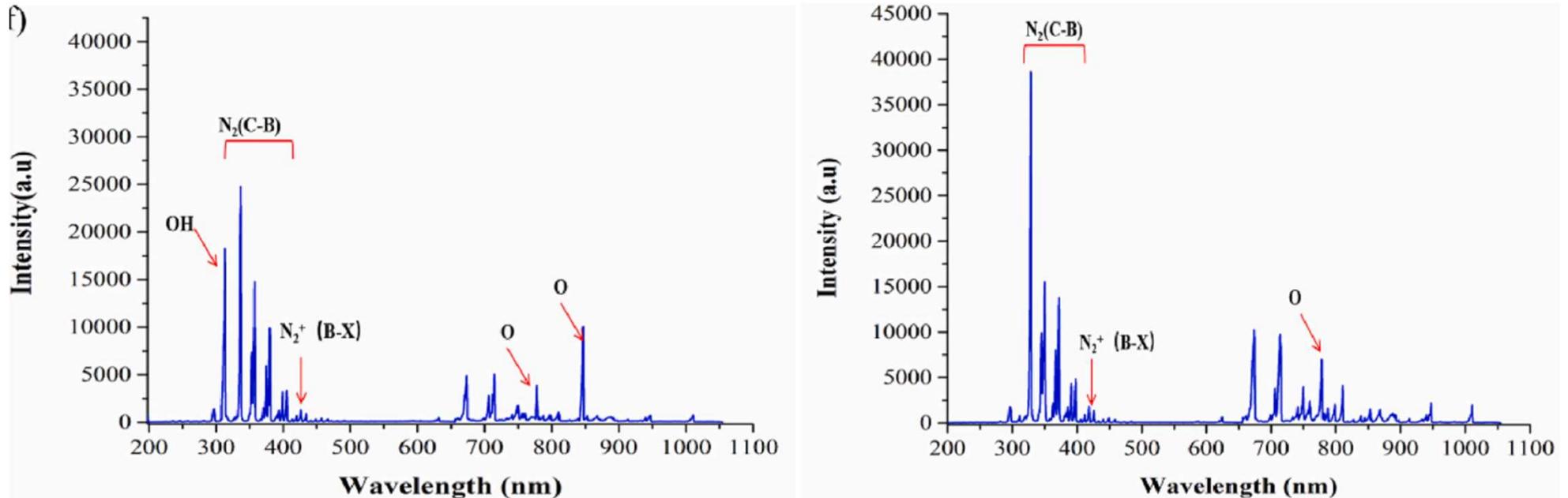


OES spectra of the air plasma



The optical emission spectrum (OES) of air plasma

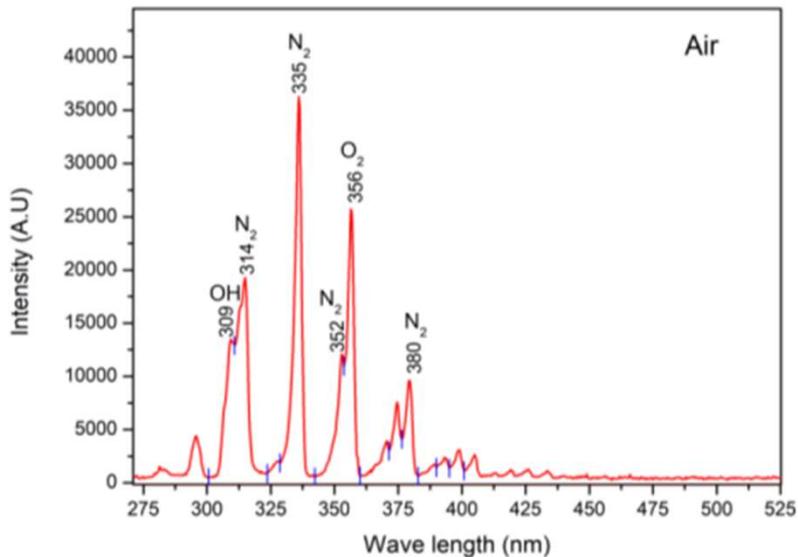
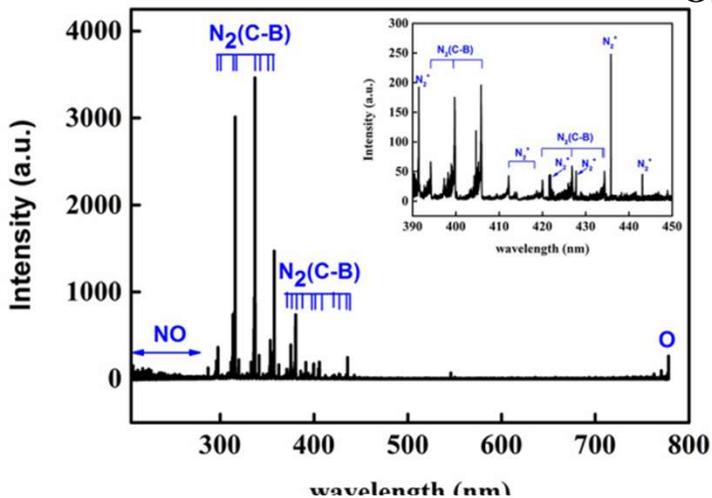
Typical emission spectra of the air plasma



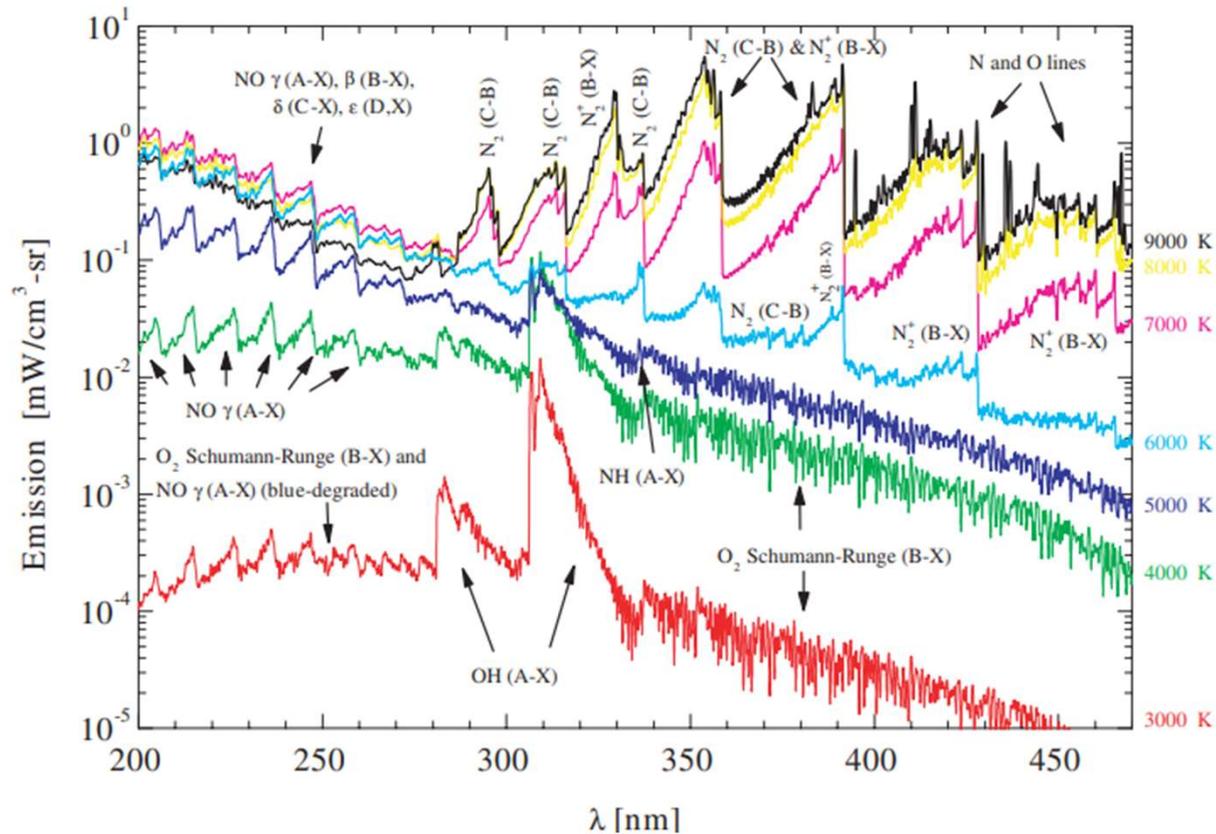
Optical emission spectra of air plasma produced by (left) the dielectric barrier discharge and (right) the plasma jet.

The type and densities of the produced species depend on the type of used plasma device

OES spectra of the air plasma



OES spectrum of the GAD air plasma

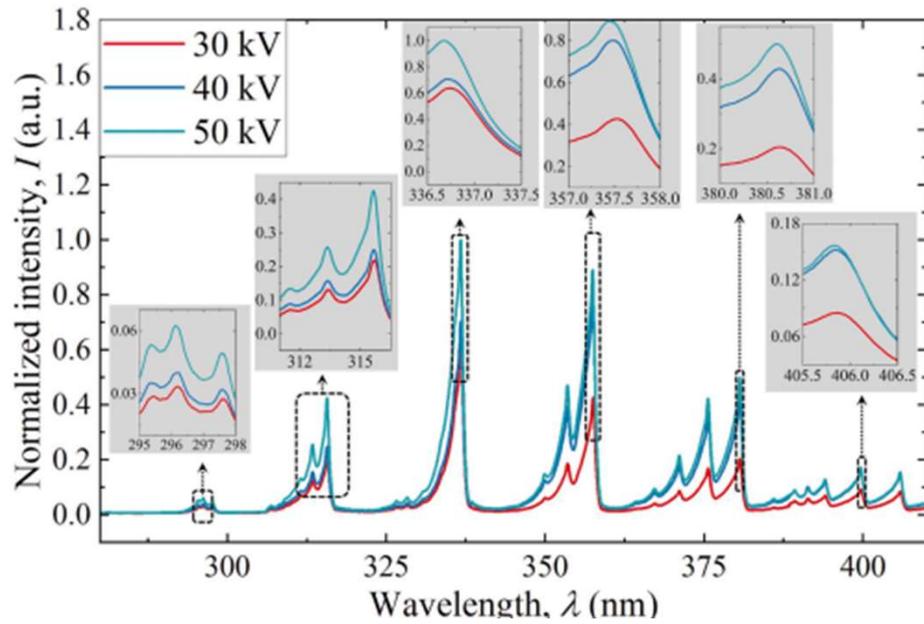


OES spectra of air at atmospheric pressure with 1.3% mole fraction of water vapour.

C.O. Laux et al. Plasma Sources Sci. Technol. 12 (2003) 125–138

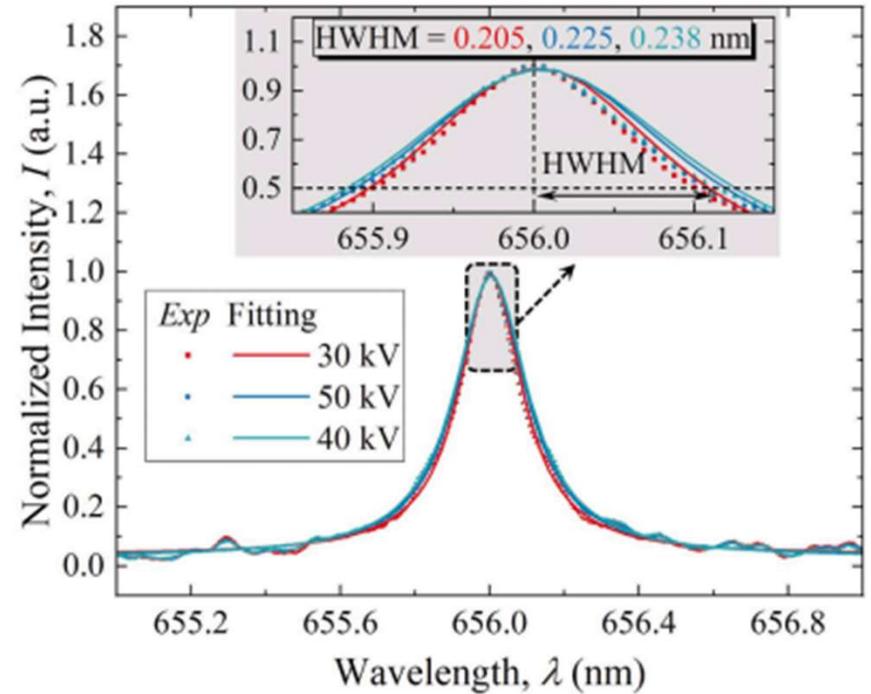
doi: 10.3389/fpls.2019.01322, DOI: <http://doi.org/10.3126/jnpysoc.v6i2.34852>

OES spectra of the air plasma

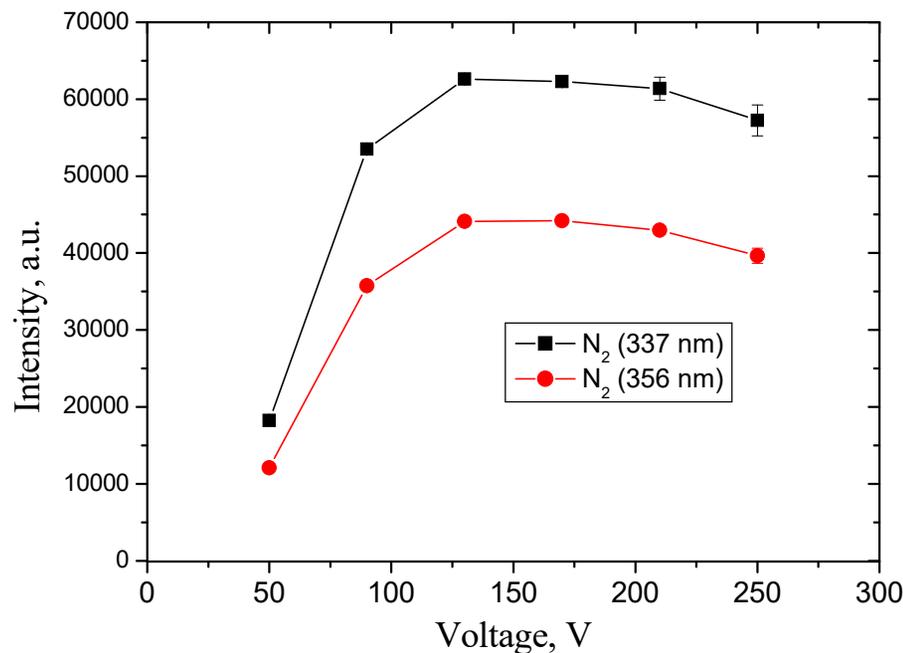
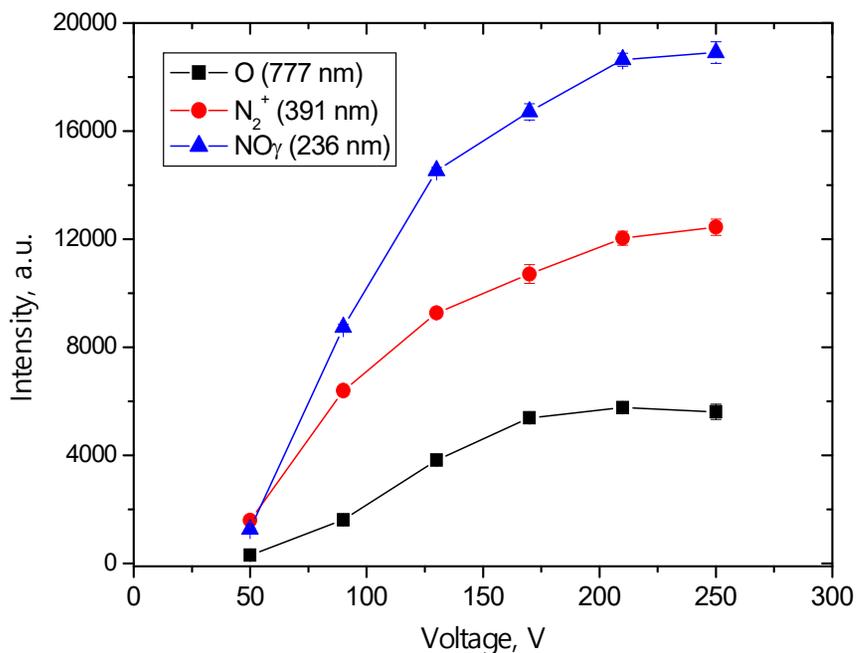


Comparison of spectral intensities of N₂ bands at 30, 40, and 50 kV.

Higher discharge voltage result in more intense emission of N₂ lines.



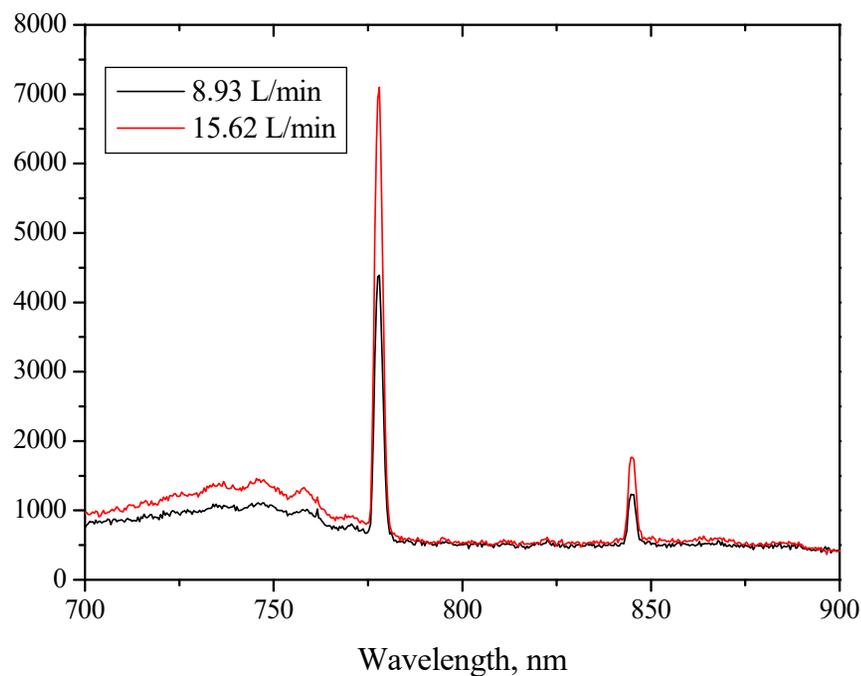
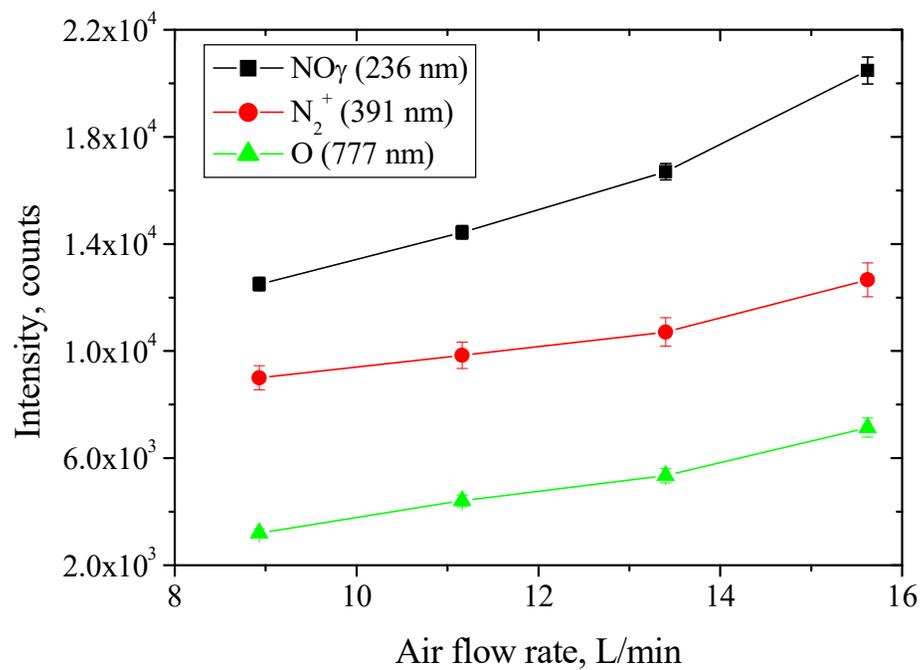
OES spectra of GAD air plasma



Type of particles	Peak position, nm
N ₂	295 nm, 316 nm, 337 nm, 356 nm, 380 nm, 375 nm, 380 nm
N ⁺ , N	221 nm, 399 nm and 434 nm, 426 nm
N ₂ ⁺	391 nm, 419 nm
NO _γ	236 nm, 246 nm, 258 nm, 283 nm
OH	306-310 nm
O	777 nm and 844 nm

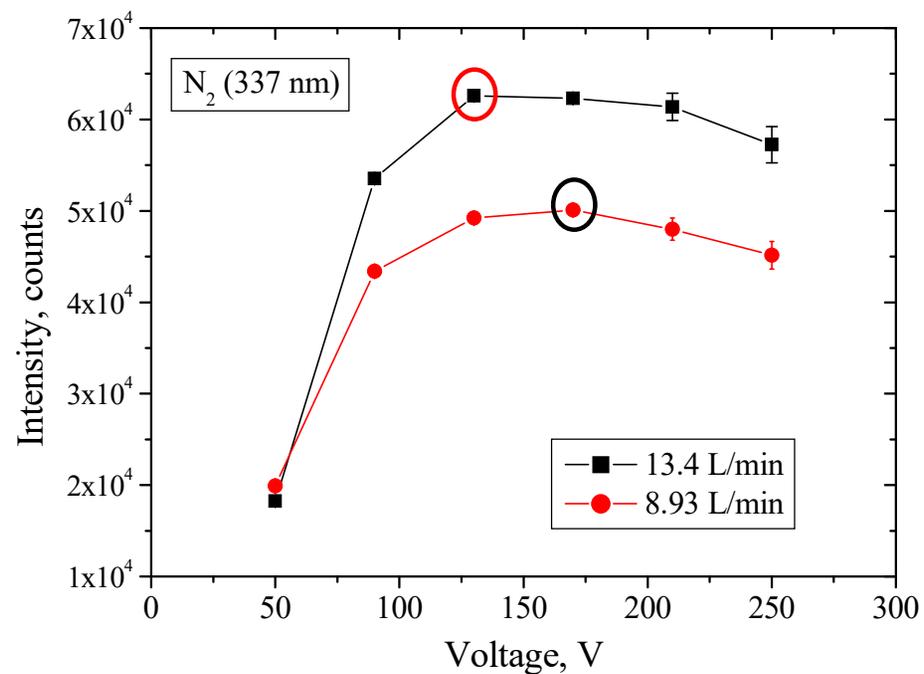
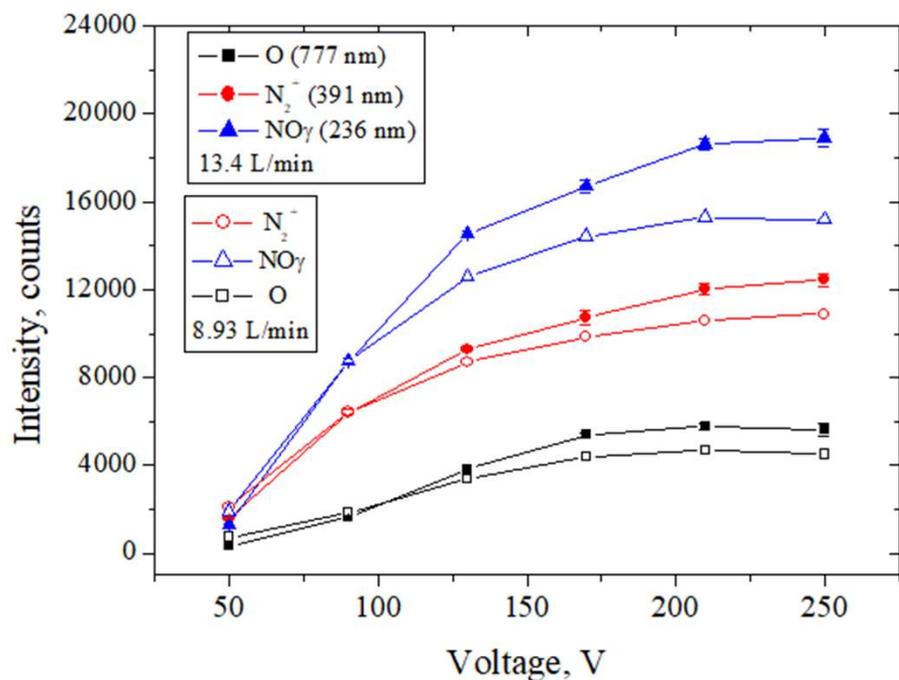
**G₁=13.4 L/min,
G₂=9.4 L/min,
U=50 to 250 V,
f=270 kHz.**

OES spectra of GAD air plasma

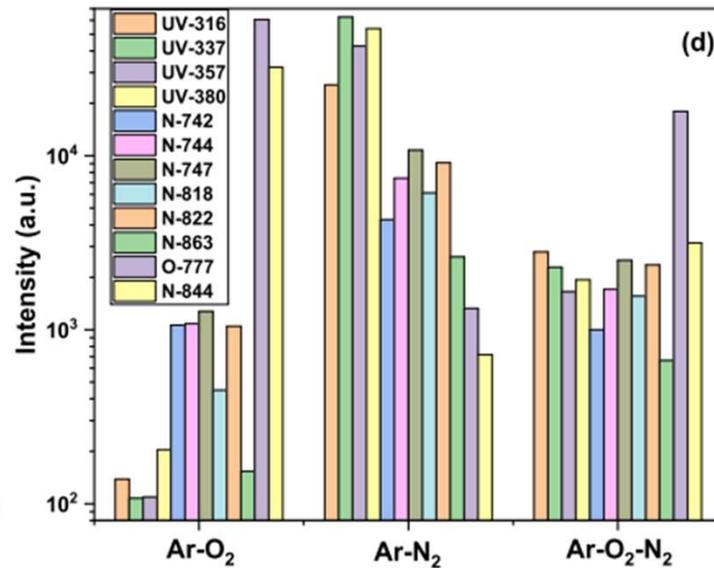
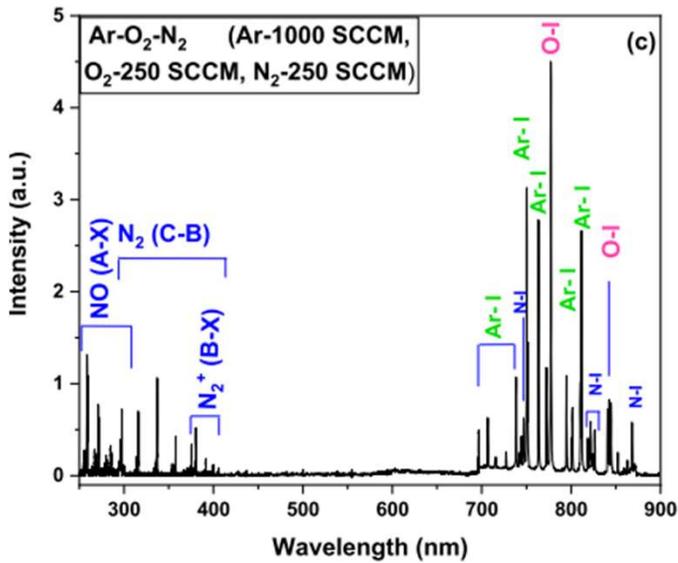
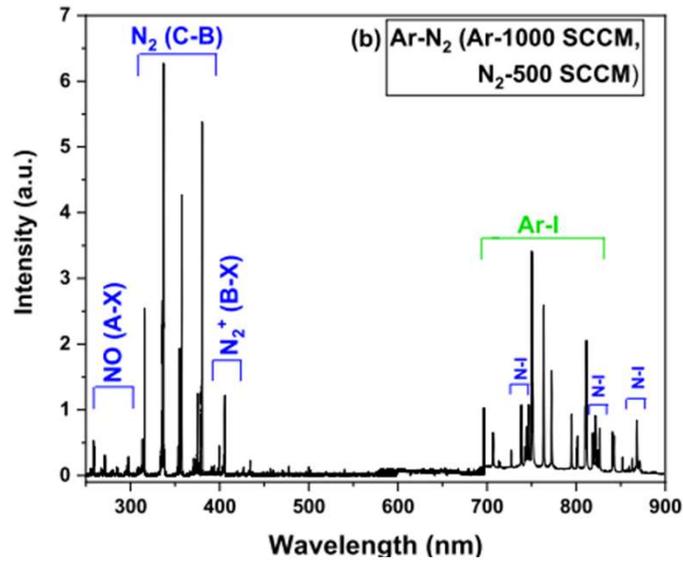
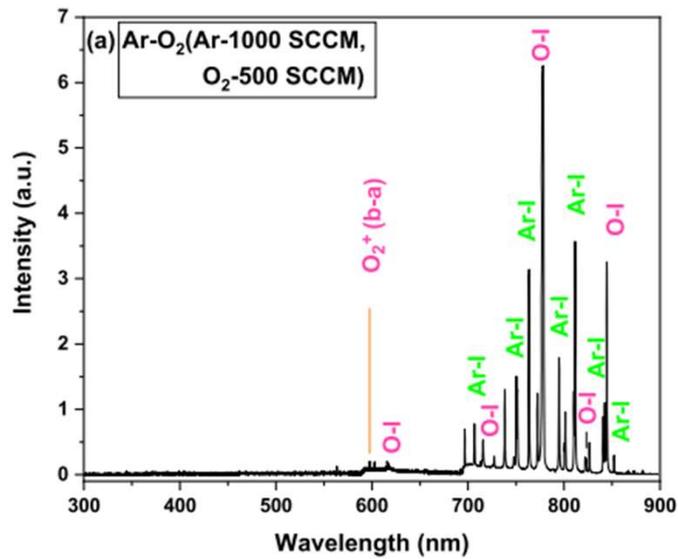


Distribution of intensities of various species, when direct air flow rate varied from ~ 8.93 L/min to 15.6 L/min, tangential air flow rate was kept at 9.4 L/min, at 170 V.

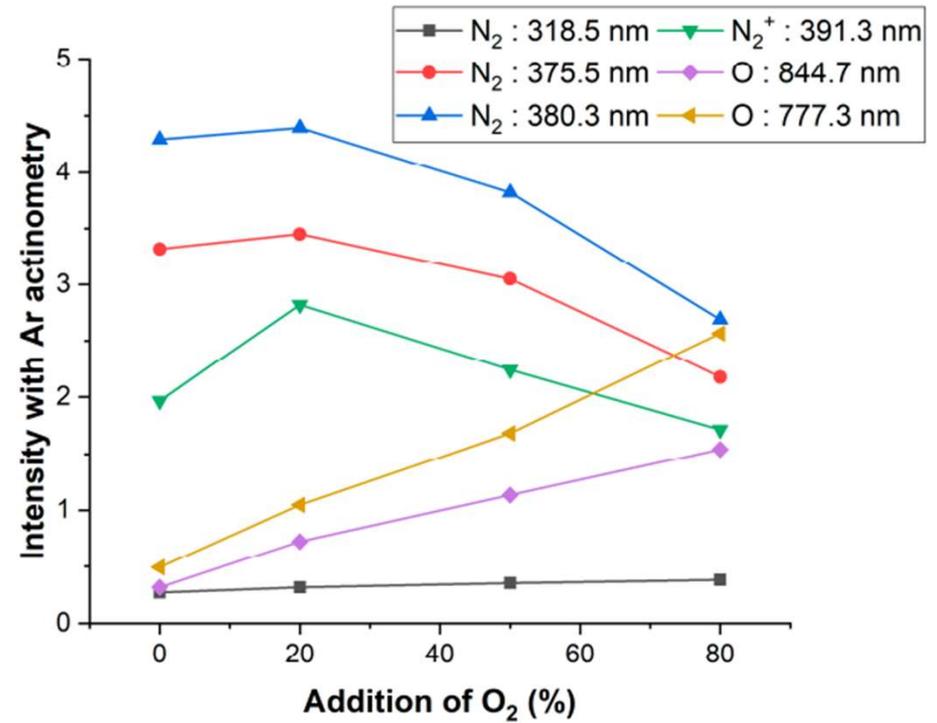
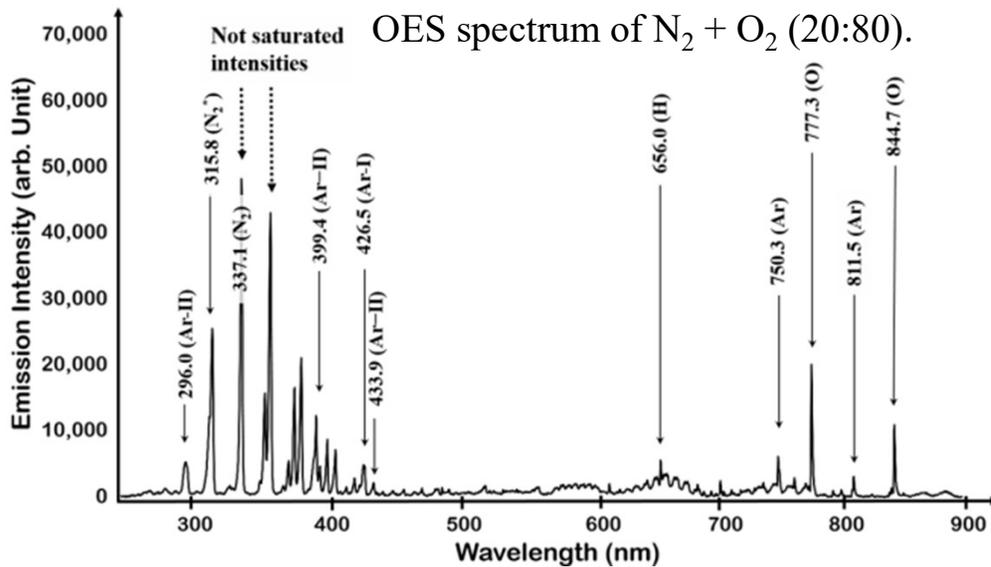
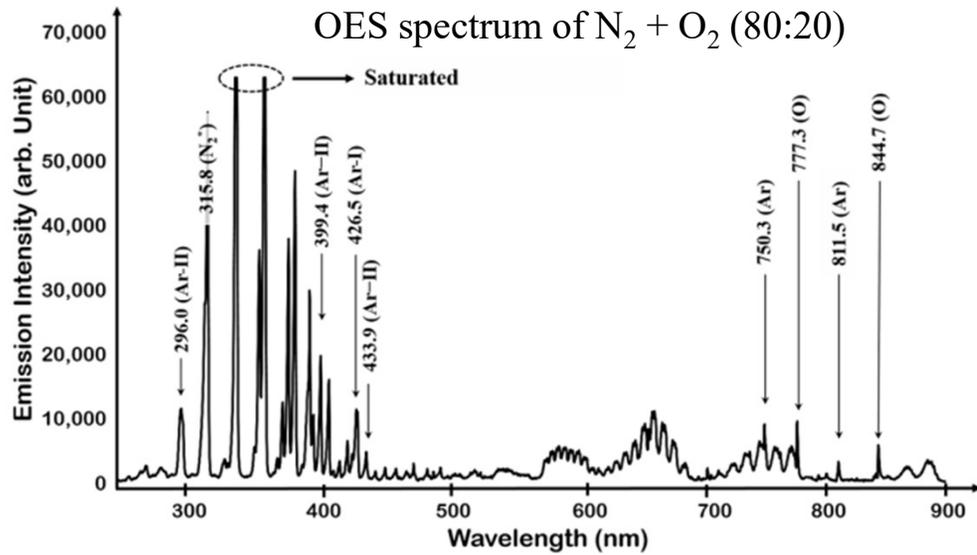
OES spectra of GAD air plasma



Distribution of intensities of various species versus output voltages, tangential air flow rate was 9.4 L/min.



Optical emission spectra of Pulsed DC Jet Plasma (a) Ar-O₂, (b) Ar-N₂, (c) Ar-O₂-N₂, and (d) normalized intensities of UV radiation, reactive nitrogen, and oxygen species.



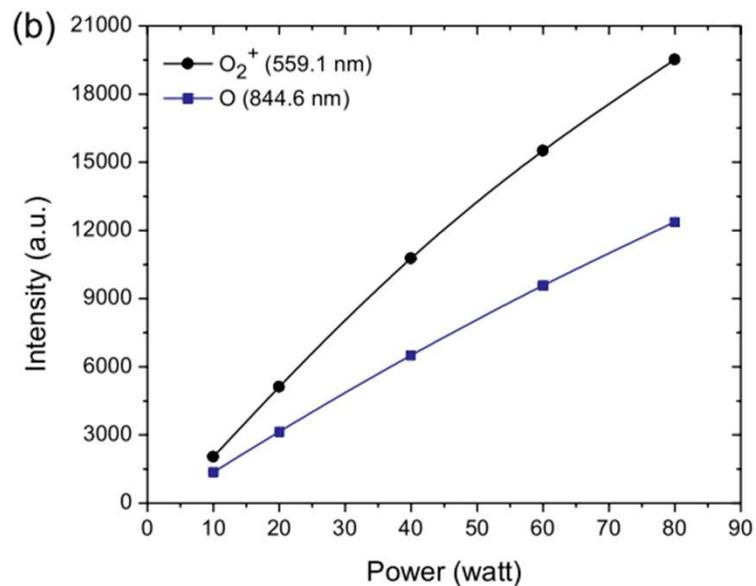
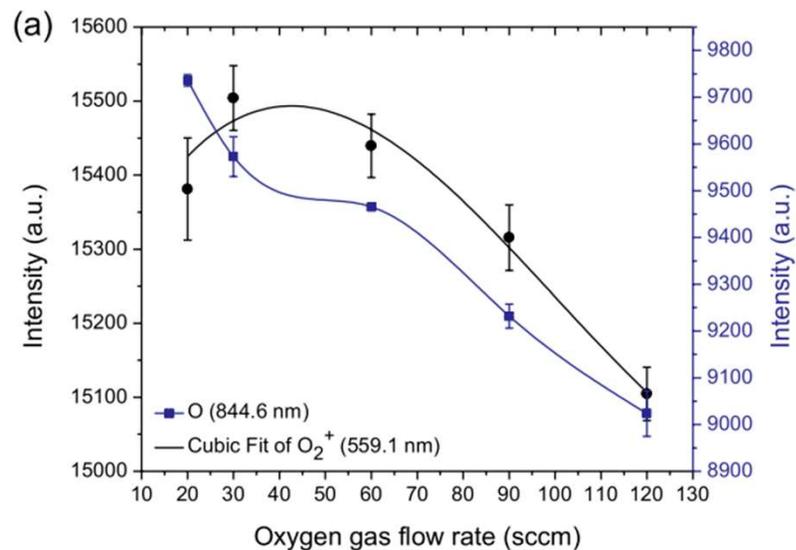
Increase of the oxygen gas result to higher intensities of O peaks and reduces N_2 peaks intensity values.

Main lines observed in OES of oxygen

Oxygen species	Transition line	Wavelength (nm)
O	$3p^5P \rightarrow 3s^5S$	777.4
	$3p^3P \rightarrow 3s^3S$	844.6
	$3d^5D \rightarrow 3p^5P$	926.6
	$4d^5D \rightarrow 3p^5P$	615.9
O_2^+	$b_4 \Sigma_g^- \rightarrow a_4 \Pi_u$	559.1
	$b_4 \Sigma_g^- \rightarrow a_4 \Pi_u$	525.7
	—	598.2
O^+	—	636.2
	—	678.9
	$3p^4D \rightarrow 3s^4P$	464.7
	—	435.3
	$3d^4F \rightarrow 3p^4D$	407.2

Increase of the oxygen gas flow result to lower intensities of O lines.

Increase of the power result to higher intensities of O lines.



Summary of reactive species detected by OES.

Gas resources of discharge	Species	Wavelength(nm)
O ₂ and Ar	O	777.2, 844.7
	OH	306–309
He and O ₂	Cu	319.4, 324.7, 327.4
	N ₂	337.1, 353.7, 357.7
	N ₂ ⁺	391
	He	447.1, 471.3, 492.2, etc.
He, Ar and N ₂	O	777.2
	H _α	565.3
	·OH (A-X)	306.4

Gas resources of discharge	Species	Wavelength(nm)
Air	OH	391
Ar	N ₂	316, 337, 357, 380, 405
	N ₂ ⁺	391
	N	120, 174.3
Air	·H	121.6
	NO (A-X)	200–300
	N ₂ (C-B)	290–430
	N ₂ ⁺ (B-X)	360–460
O ₂	·OH	283, 309
	H _β	468
	O ⁻	777, 844
Air	·OH (A-X)	309
	H _α	656
	H _β	486
	H _γ	434
	O	777, 843
	N ₂	357, 380, 391, 427

Significant challenges remain with OES techniques due to:

- Presence of extremely steep gradients of temperatures and species concentrations across a relatively small volume requiring a high spatial resolution of the optical setup.
- Relatively wide range of radiation intensities' variations across the plasma volume (typically more than three orders of magnitude) which imposes an important constraint on the choice of the sensors to be used for these measurements.
- Dynamic fluctuations of the plasma source with time at relatively high frequencies.
- Presence of stray radiation from the plasma fringes which can increase the level of the background noise in the measurement.
- Large volume of data to be acquired and processed which makes automation an essential requirement.

Advantages of Optical Emission Spectroscopy

- **High accuracy:** OES is capable of providing highly accurate results, making it a reliable method for determining the chemical composition of a plasma. This accuracy is due to the unique spectral signature that each element emits when excited, allowing for precise identification and quantification.
- **Fast analysis:** OES is a fast analytical method, providing results in seconds or minutes, depending on the sample size and complexity. This speed makes OES ideal for use in industrial settings where quick results are crucial.
- **Versatility:** OES can be used to analyze a wide range of samples, including liquids, solids, and gases, plasma, making it a versatile technique for many different applications.
- **Non-destructive:** Unlike other analytical methods, OES is non-destructive, meaning that the sample remains unchanged after testing. This allows for the analysis of valuable or rare samples without damaging them.
- **Real-time analysis:** OES can be performed in real-time, providing up-to-date information on the composition of a plasma. This makes OES ideal for use in process control applications where real-time analysis is required.
- **Cost-effective:** OES is a cost-effective analytical technique, particularly when compared to other methods that require sample preparation or special equipment. This makes OES an attractive option for businesses and organizations looking to reduce costs while still obtaining accurate results.

Acknowledgments



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Thank you for your attention